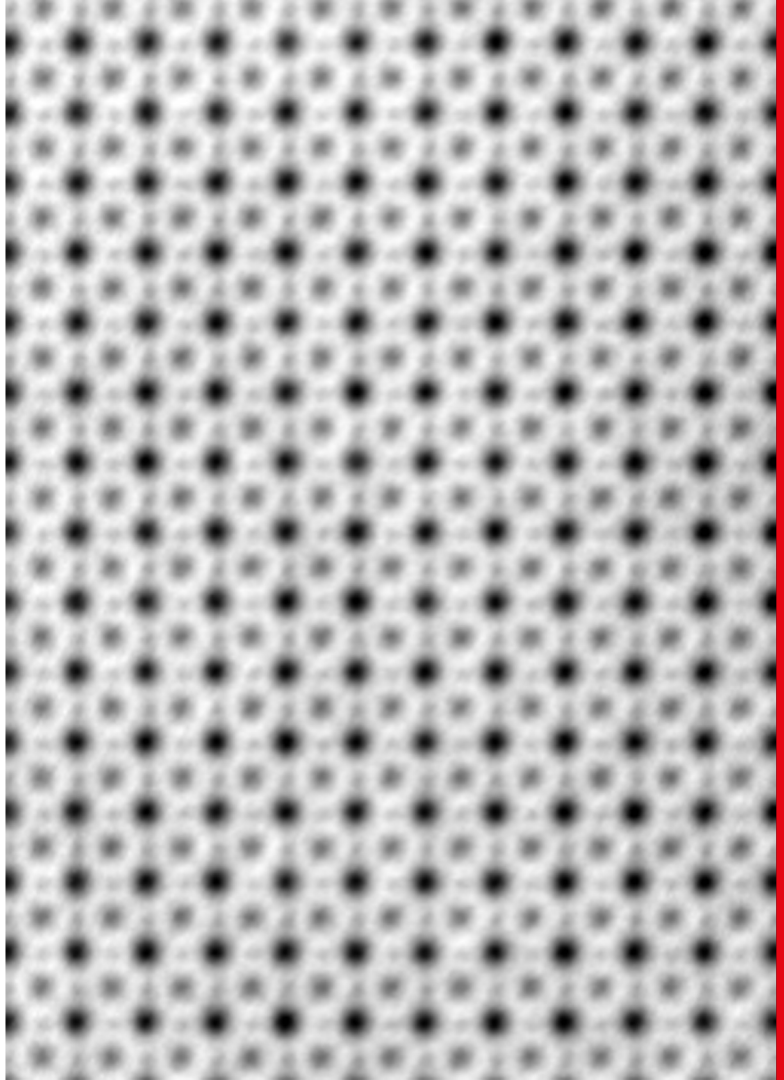


Transmission Electron Microscopy (TEM)

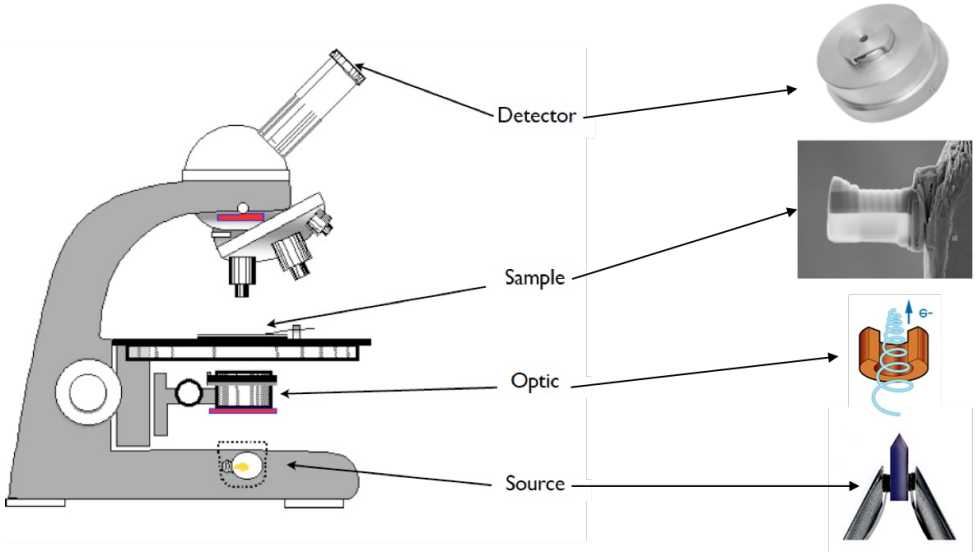
CH-633 - Online edition

Emad Oveisi

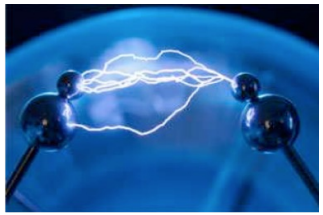
Contents

Introduction to TEM

Emad Oveisi



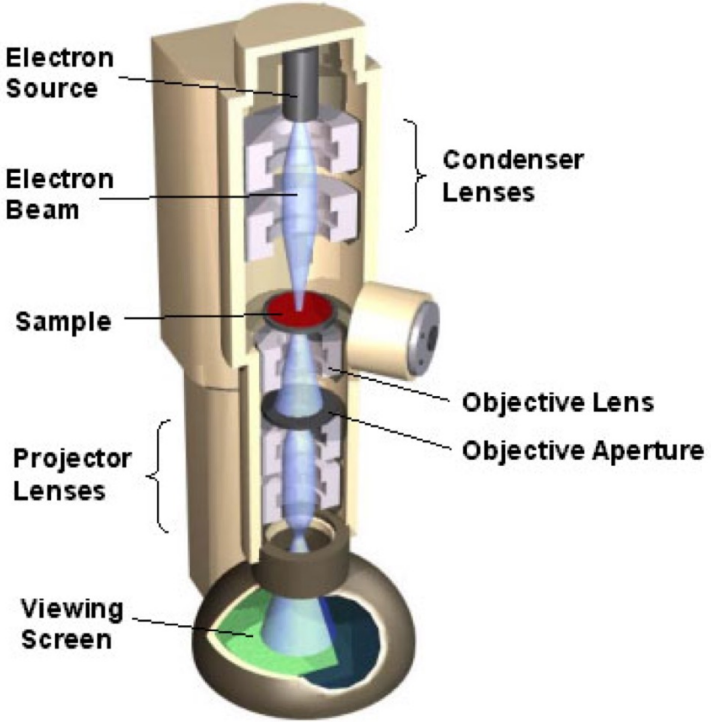
Visible light

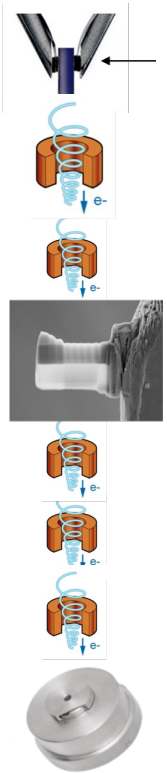


Fast electrons
100–300 keV
(0.5–0.8 *c* !)

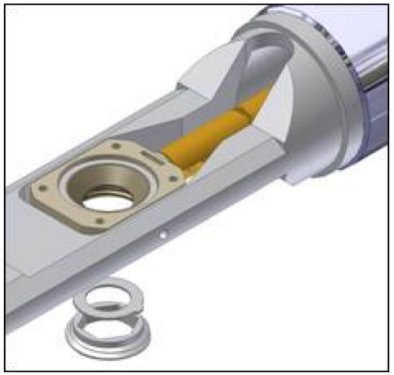
Can consider analogous to projection light microscopy, but with better resolution

Introduction to TEM





Double Cs-corrected FEI Titan-Themis @ CIME-EPFL



Specimen should be electron transparent: several nanometers thick

Why fast electrons?

	Advantageous	Disadvantageous
Visible light	Not very damaging Easily focused Eye detector	Long wavelengths (400 nm)
X-rays	Small wavelength (Angstrom) Good penetration	Hard to focus Damage sample
Neutrons	Low sample damage Small wavelength (pm)	How to produce? How to focus?
Electrons	**Small wavelength (pm)** **Can be focused to a sub-Å size probe** **Wave-particle duality**	**Damage sample** **Poor penetration** (< x00 nm)

High energy electrons have a short wavelength (e.g. 2.5 pm @ 200 keV)
Easy to produce high brightness electron beams
Easy to manipulate: focused
Interact strongly with matter

Electron microscopes are used not only for obtaining good resolution images but also:

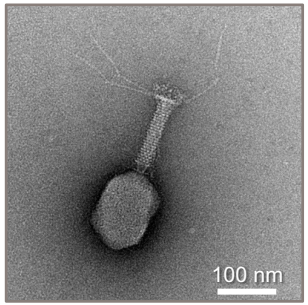
- **can be used as a diffractometer**
- **for chemical analyses (EDX and EELS)**
- **for imaging/measuring electric-, magnetic-, or strain-field in the sample**
- **for measuring optoelectronic properties (e.g. cathodoluminescence), …**

***Aberrations & instabilities ➔ Actual resolution around 25-50 λ, but atomic/sub-Å resolution possible in TEM**

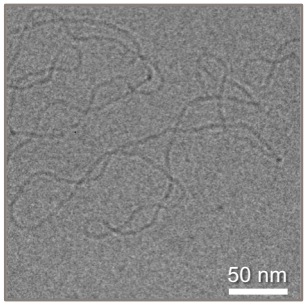
Applications of TEM

Biology and life science

a



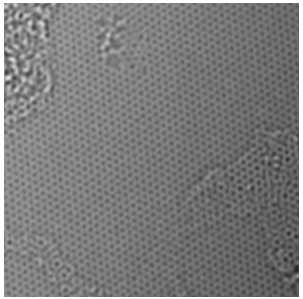
T4 virus [a]
A bacteriophage that infects Escherichia coli bacteria



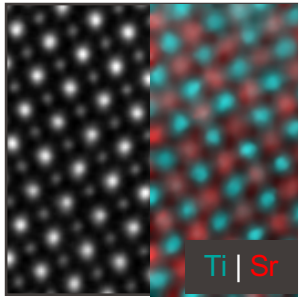
DNA molecule [a]

Chemistry & materials research

c



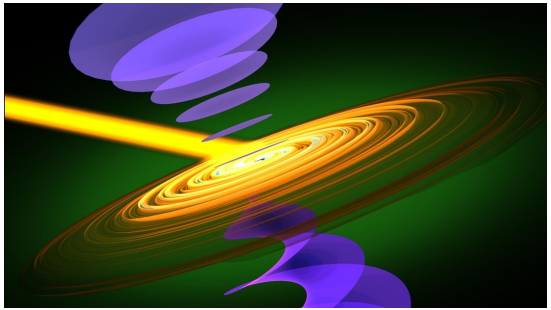
d



Imaging and spectroscopy at atomic resolution [c,d]

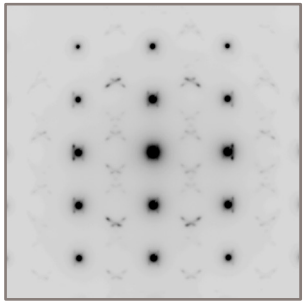
Fundamental physics

b



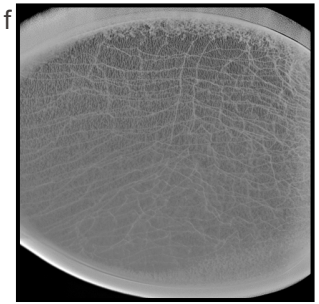
Ultrafast electron vortex beams [b]

e



Crystallographic studies [e]

f



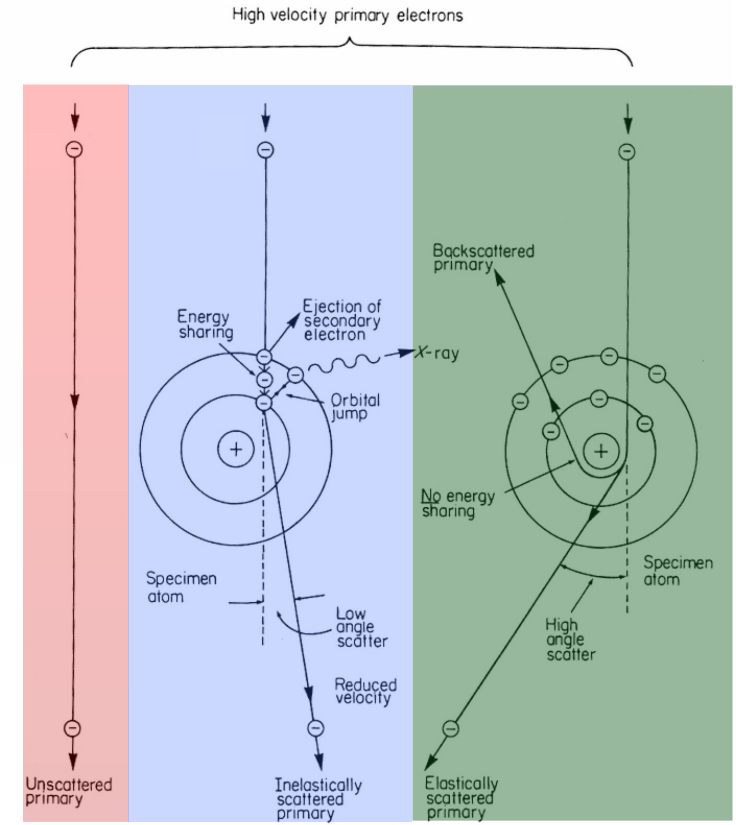
Analyzing crystal defects [f]

[a] Images courtesy of Dr. D. Demurtas, CIME-EPFL.
[b] Vanacore et al., Nature Materials (2019).

[c] Huang et al., Nat. Comm. 2018.
[f] Oveisi et al., Ultramicroscopy (2017).

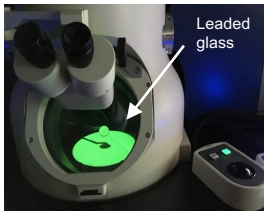
[e] Oveisi et al., Scripta Mat. (2013).
[d] Bencan et al., Nat. Comm. (2021).

e- matter interactions



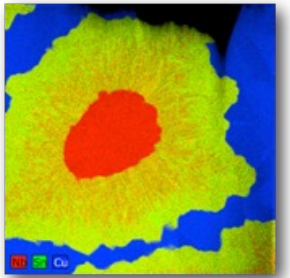
Inelastic events: The result is a **transfer of beam energy** to the specimen atom (**energy loss**) and a potential expulsion of an electron from that atom as a **secondary electron (SE)**.

If the vacancy due to the creation of a secondary electron is filled from a higher level orbital, an X-Ray or Auger characteristic of that energy transition is produced.



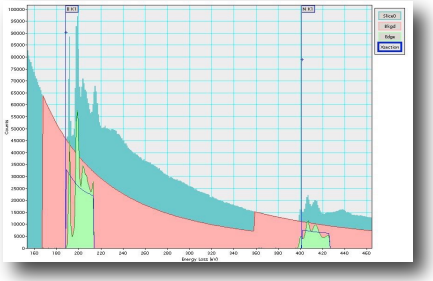
That's why TEMs are shielded!

Characteristic X-rays



Chemical composition

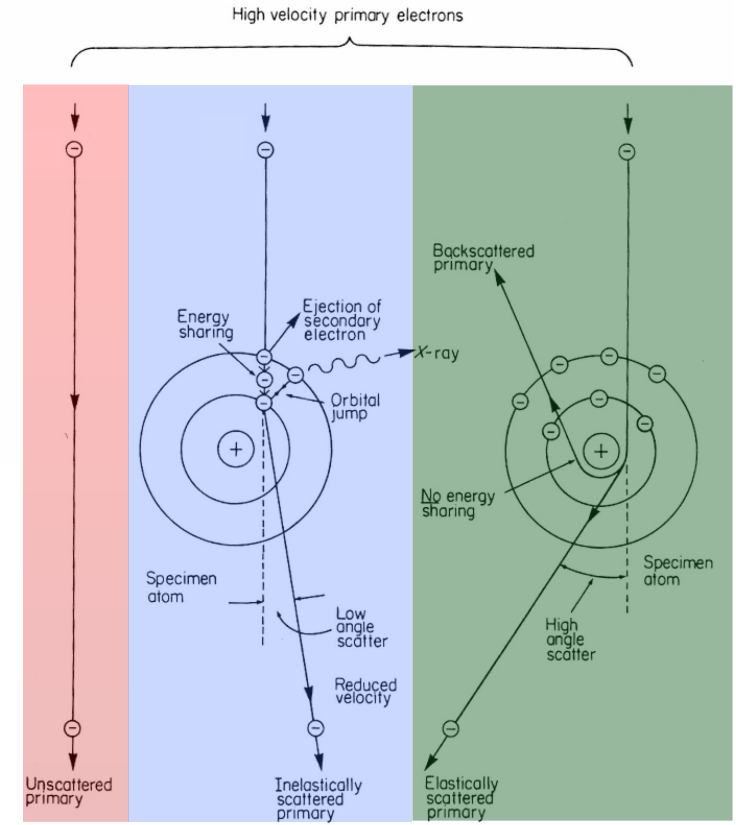
Electron energy-loss spectrum



Chemical composition, band-gap & optical properties

Emad Oveisi

e- matter interactions

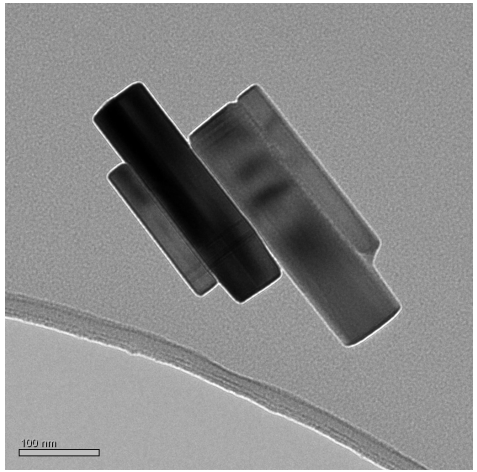


Elastic events occur when a beam electron interacts with the electric field of the nucleus or electron cloud of a specimen atom (Coulomb forces), resulting in a change in the direction of the beam electron **without a significant change in the energy** of the beam electron (< 1 eV).

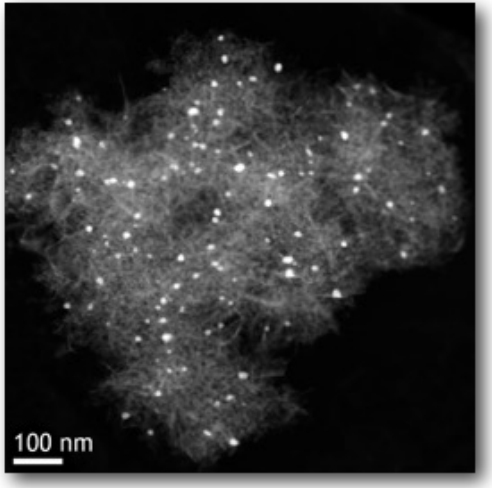
Coulombic interaction within the electron cloud, Low-angle scattering
Coulombic attraction by the nucleus, Higher-angle scattering

Thicker specimen or larger nucleus → More scattering

GaN nano wires



Mass/thickness contrast
Bright-field TEM image



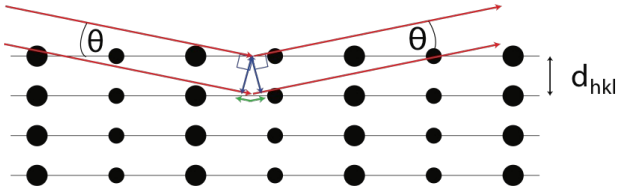
Pt catalyst particles on Al_2O_3

Mass/thickness contrast
HAADF-STEM image

e^- as wave & Bragg scattering

Emad Oveisi

For X-ray diffractometer



X-ray scattering:
Path difference between reflection from planes distance d_{hkl} apart
$= 2d_{hkl}\sin\theta$

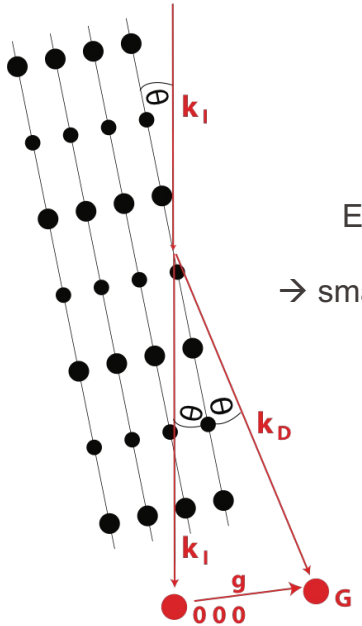
Bragg law

$n\lambda = 2d_{hkl}\sin\theta$

or

$\lambda = 2d_{nhnknl}\sin\theta$

For TEM electrons come from top, but otherwise geometrically the same



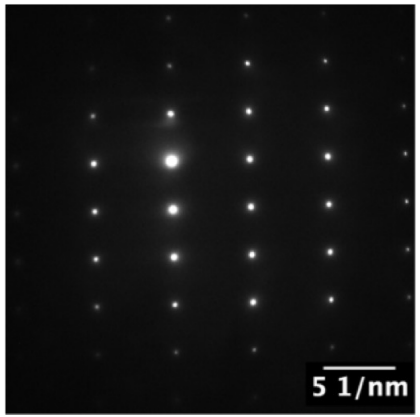
Electron diffraction: $\lambda \sim 0.001$ nm
therefore: $\lambda \ll d_{hkl}$
→ small angle approximation: $\lambda \approx 2d_{nhnknl}\theta$

→ Bragg diffraction at angle 2θ

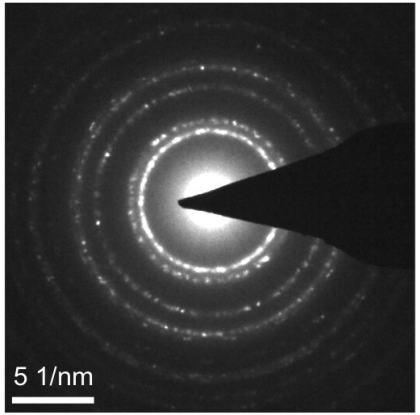
Emad Oveisi

e⁻ as wave & Bragg scattering

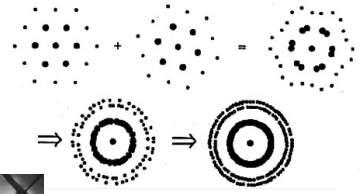
Electron diffraction pattern

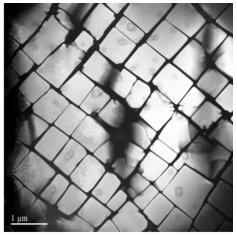


Spot pattern from a single crystal
Spots represent different (hkl) planes

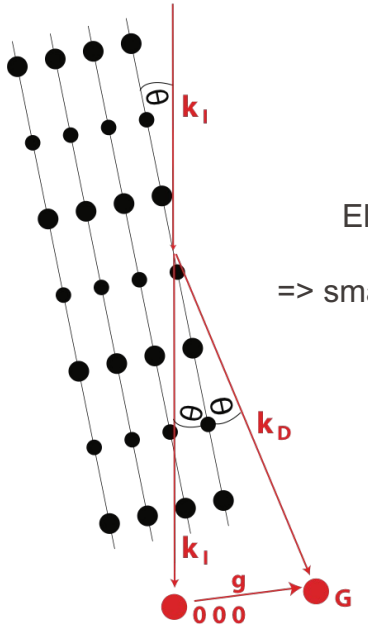


Ring pattern as many crystallites oriented differently in diffraction conditions





Therefore TEM gives image & diffraction!



Electron diffraction: λ ~ 0.001 nm
therefore: $\lambda \ll d_{hkl}$
=> small angle approximation: $\lambda \approx 2d_{nhnknl}\theta$

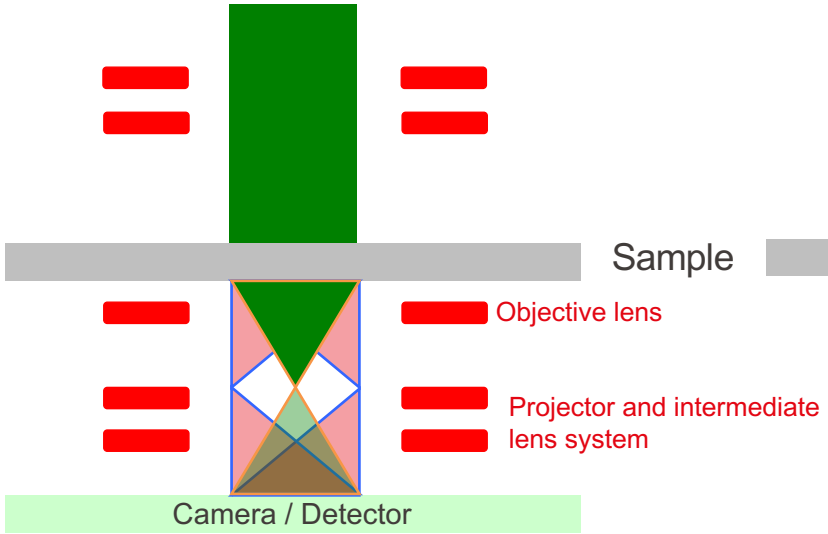
=> Bragg diffraction at angle 2θ

Emad Oveisi

TEM operation modes

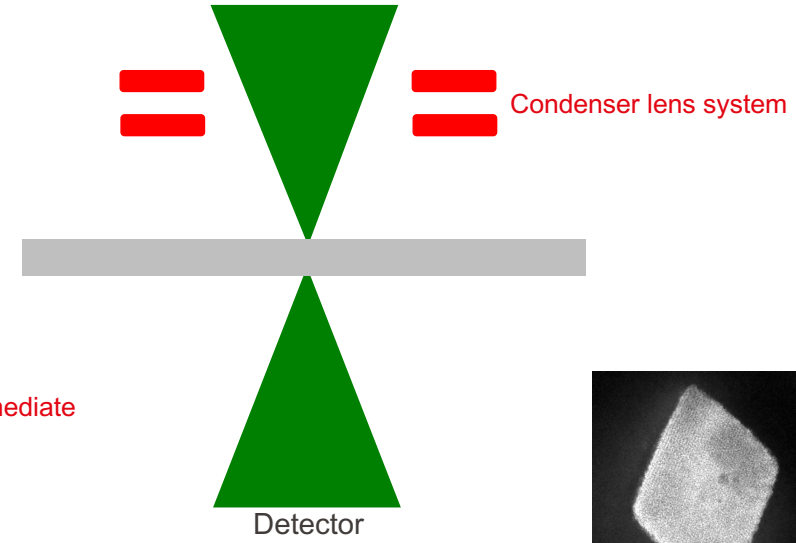
Conventional TEM

Electron beam (60-300 keV)



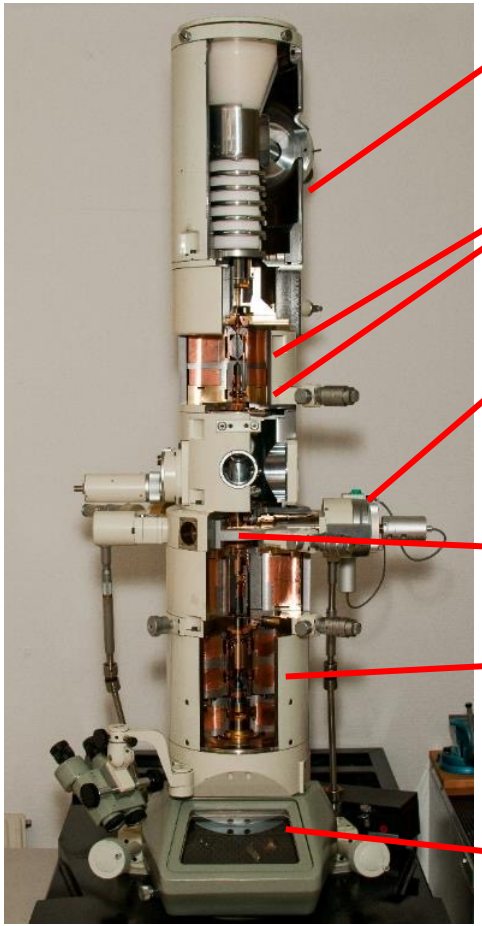
Scanning mode (STEM)

Electron beam (30-300 keV)



Fe-based metal-organic framework

2D projection of a 3D object



Electron Source

Produces high energy, large current, and high coherence electron beams necessary for generating diffraction patterns and high spatial resolution images

Condenser system and condenser aperture

Controls spot size and illumination area on sample (beam intensity)

Specimen holder and goniometer

Objective lens and objective aperture

Images sample and is the strongest lens in the system

Intermediate and projector lenses

Changes modes from diffraction to imaging

Controls magnification

Detectors / Camera

Various different configurations designed to collect signals produced by the high-energy electron beam

Image/Contrast mechanisms

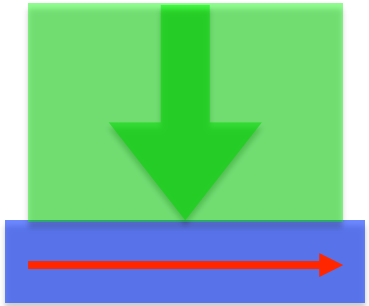
Emad Oveisi

- **Image formation in TEM**
  - Image and diffraction modes
  - Bright- and dark-field modes
  - High-resolution TEM
- **Image contrast in TEM**
  - Mass-thickness contrast
  - Diffraction contrast
  - Phase contrast

Image formation in TEM

Emad Oveisi

Parallel incident e⁻ beam; $\lambda \approx 0.02–0.03$ Å



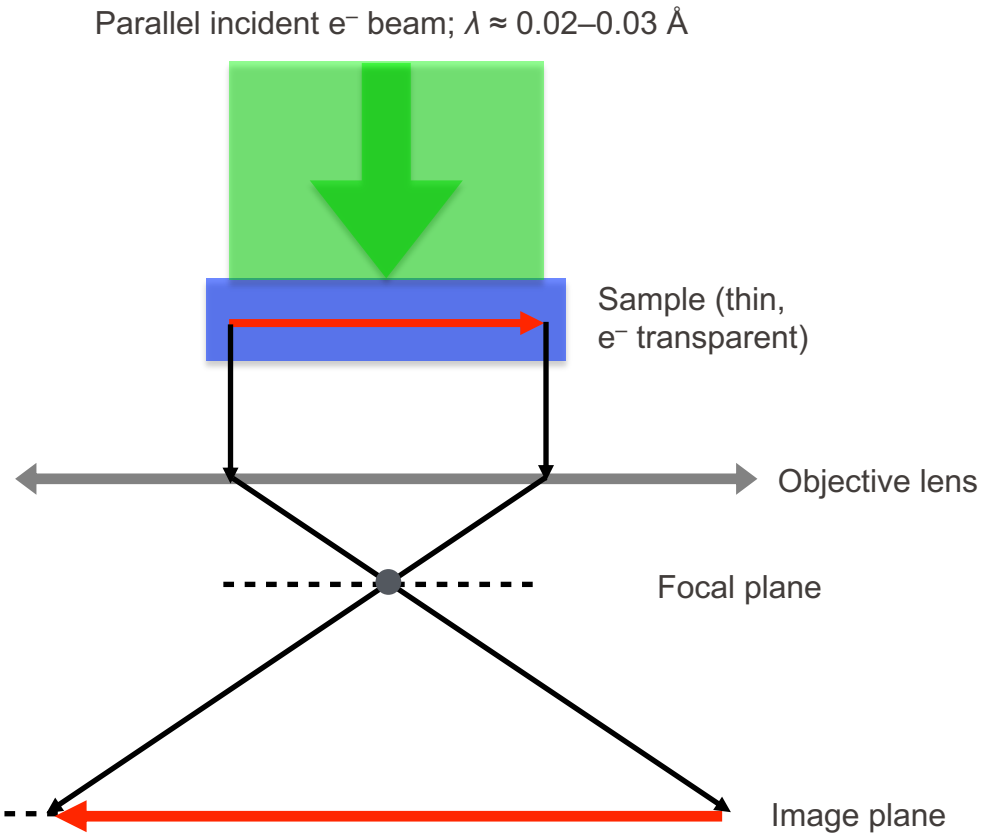
Sample (thin, e⁻ transparent)

Objective lens

Focal plane

Image plane

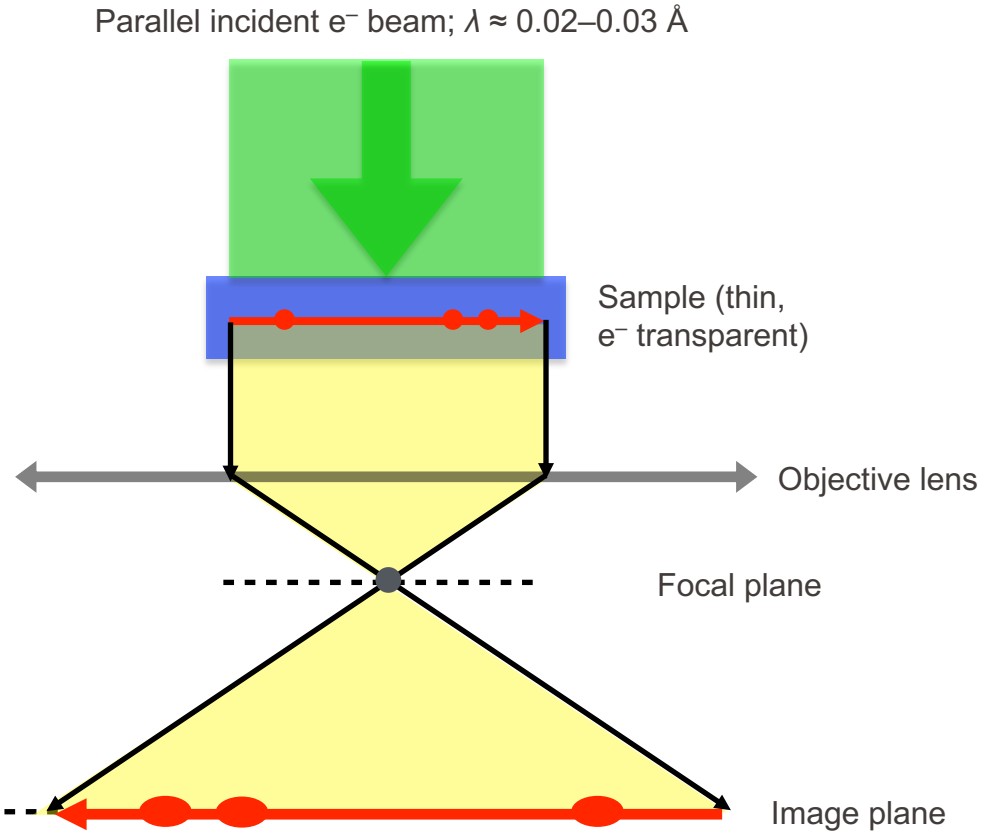
Image formation in TEM



Emad Oveisi

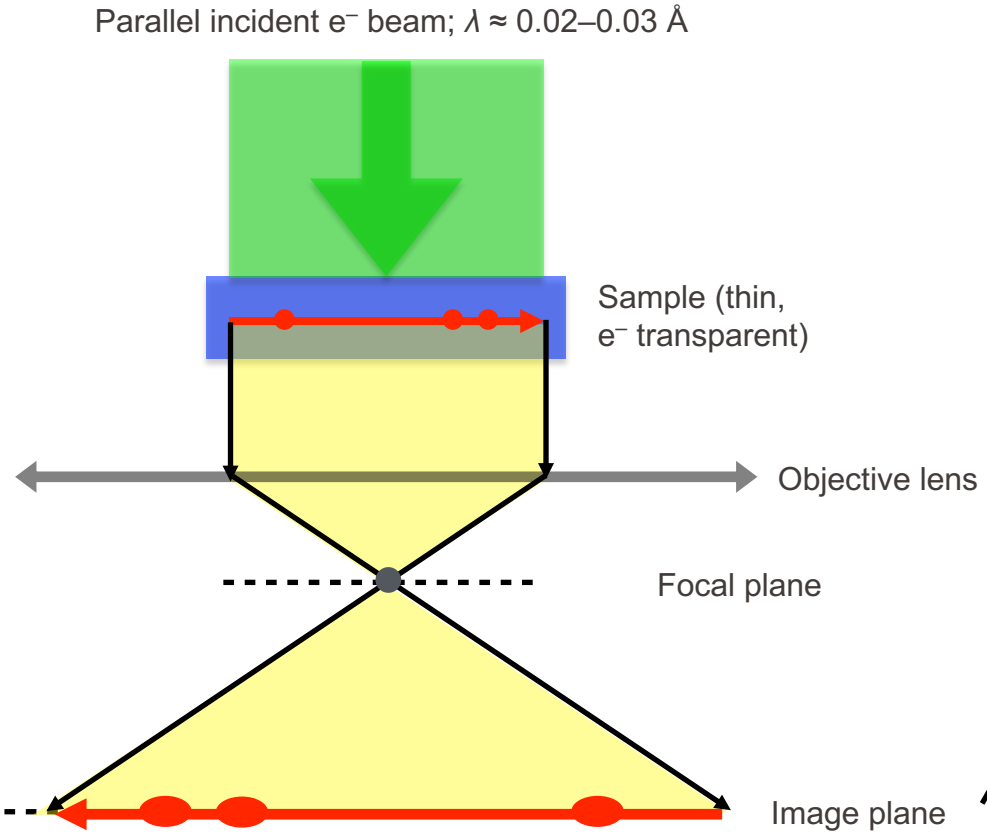
Image formation in TEM

Emad Oveisi



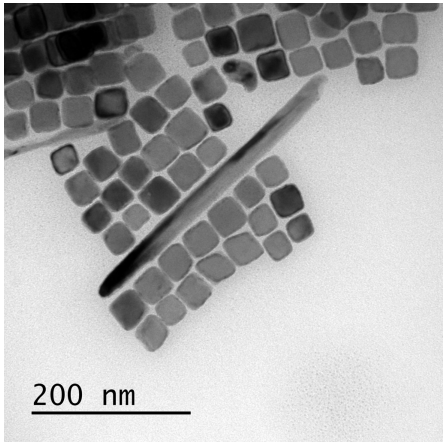
Emad Oveisi

Image formation in TEM



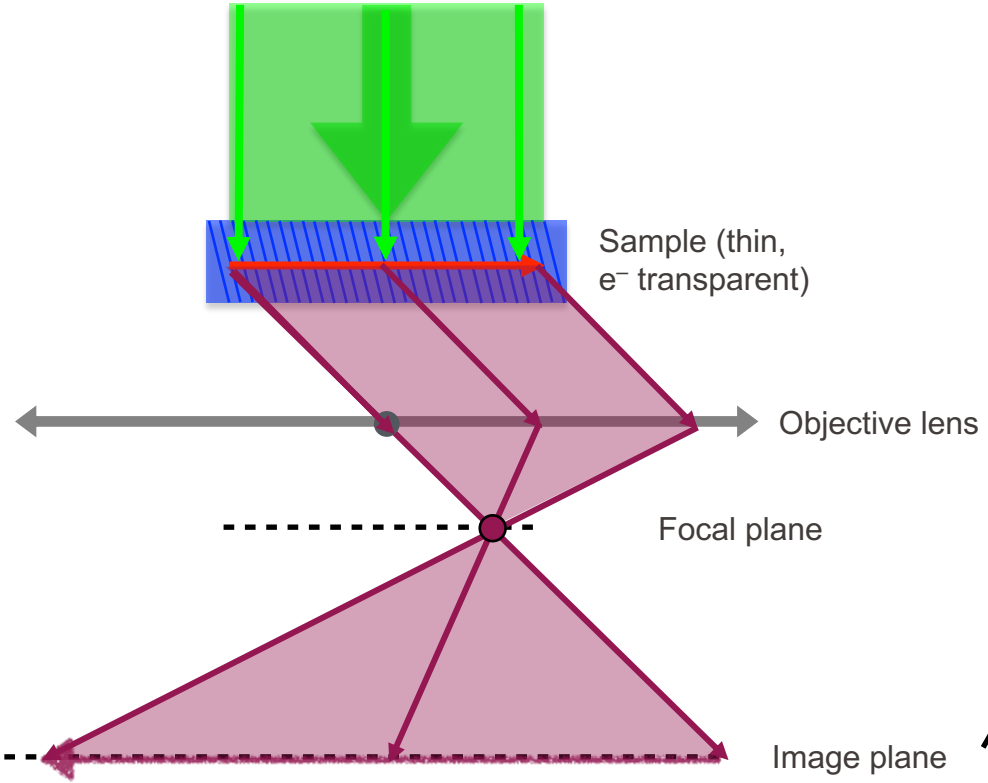
Why some cubic particles appear darker than others?

Cubic particles (≈ 40 nm) of Cu

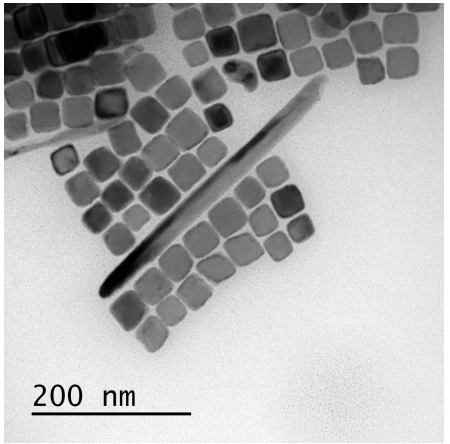


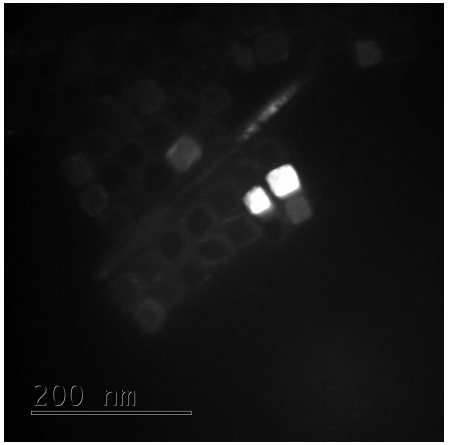
Bright-field image:
made by directly transmitted electrons

Image formation in TEM



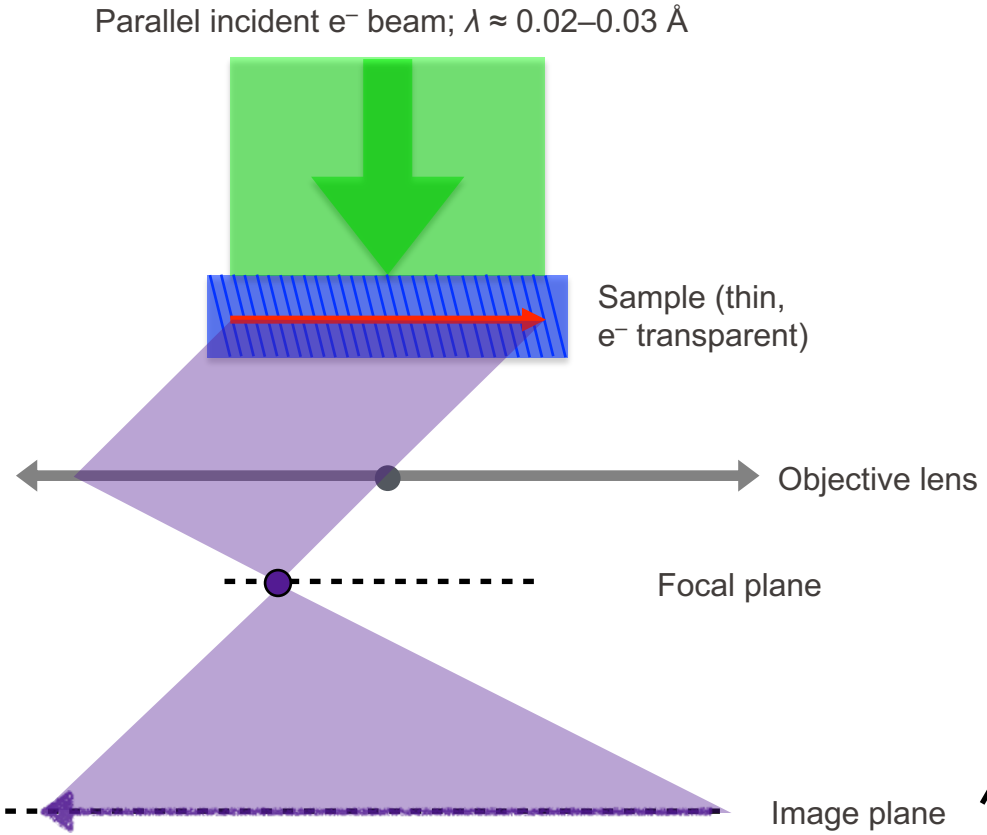
Bright-field image



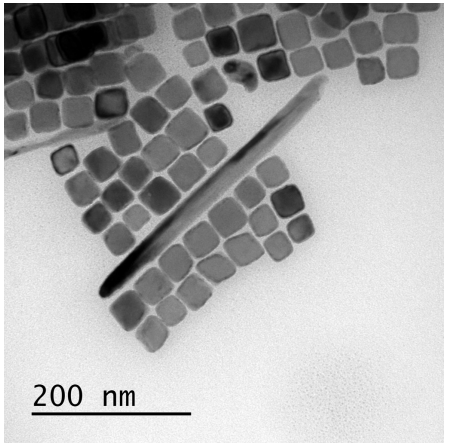


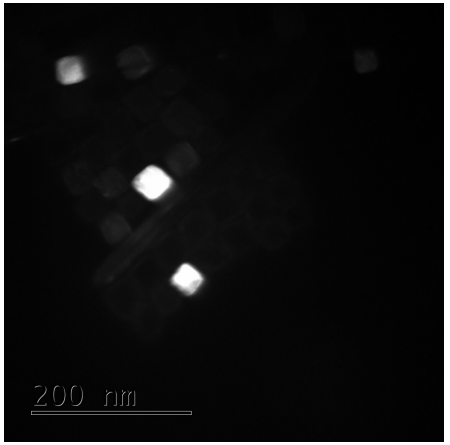
Dark-field image:
made by selected diffracted electrons

Image formation in TEM



Bright-field image



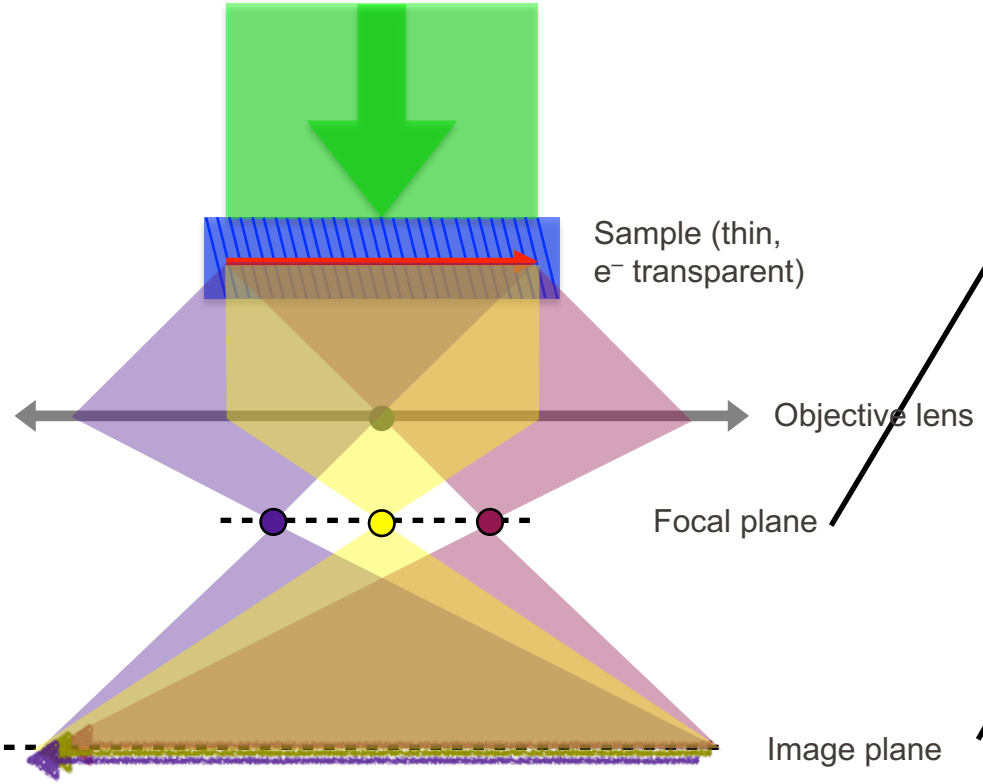


Dark-field image:
made by selected diffracted electrons

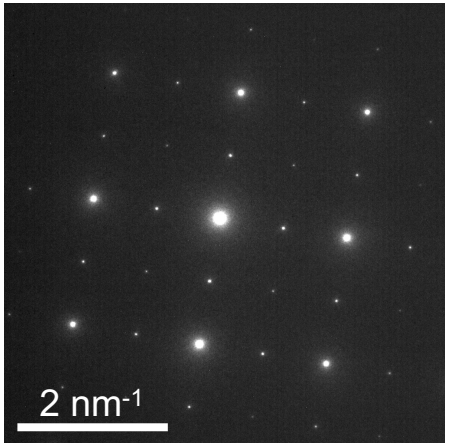
Image formation in TEM

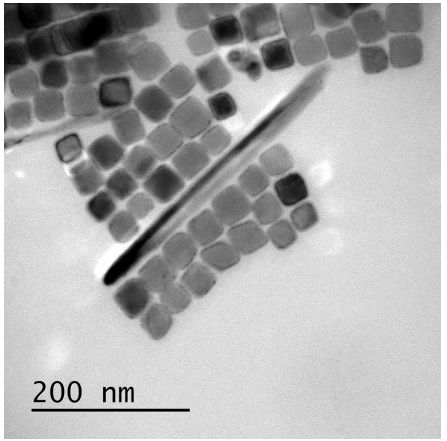
Emad Oveisi

Parallel incident e⁻ beam; $\lambda \approx 0.02–0.03$ Å



Electron diffraction pattern

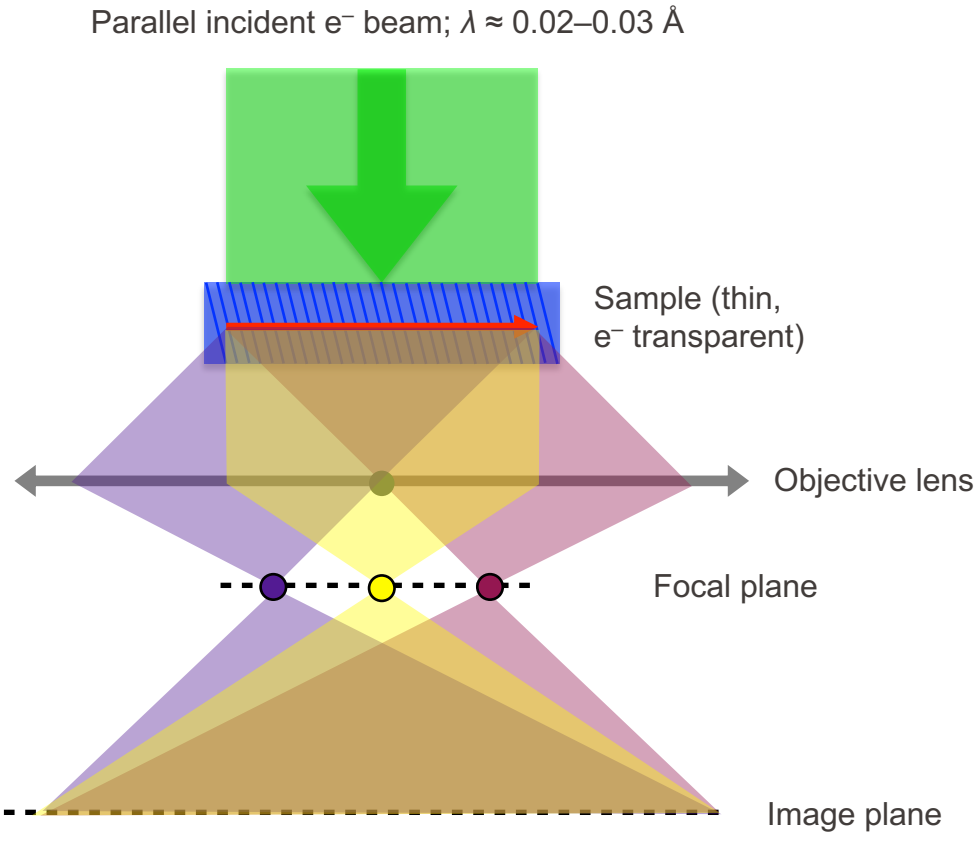




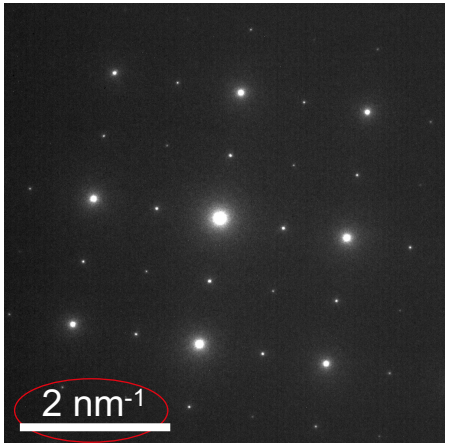
Ghost image:
Superposition of images made by direct and diffracted electrons

Image formation in TEM

Emad Oveisi



Electron diffraction pattern

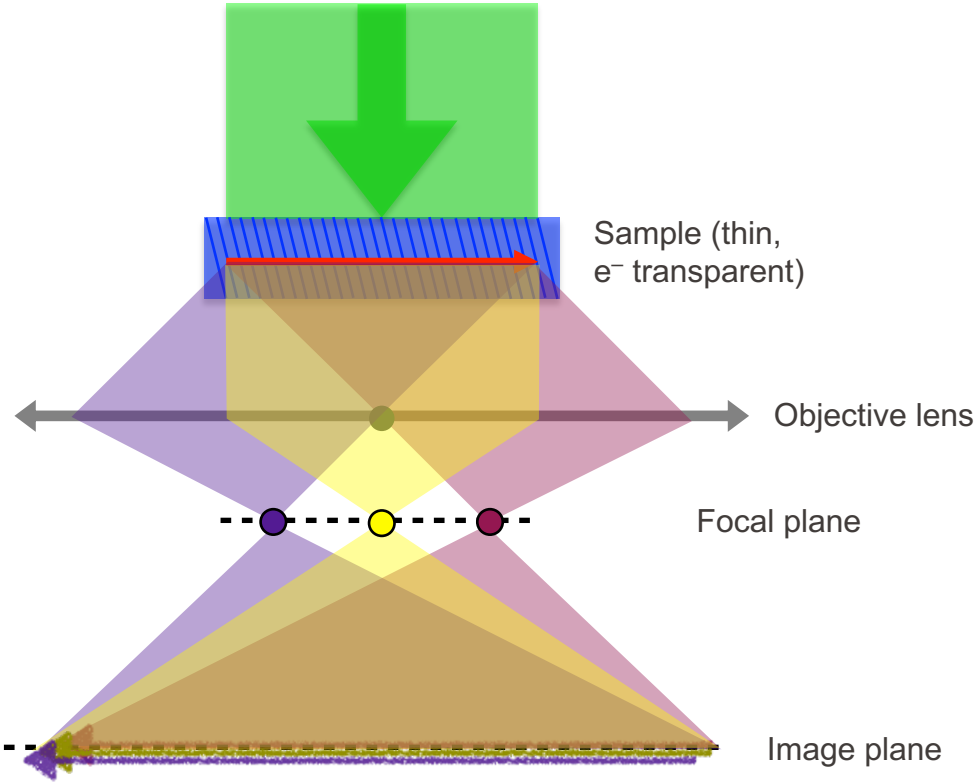


- *In back focal plane of objective lens parallel rays focused to point*
- *Diffraction – coherent scattering – creates sets of parallel rays from different crystal planes*
- *Focusing of these parallel rays in back focal plane creates spots of strong intensity:* ***the diffraction pattern***

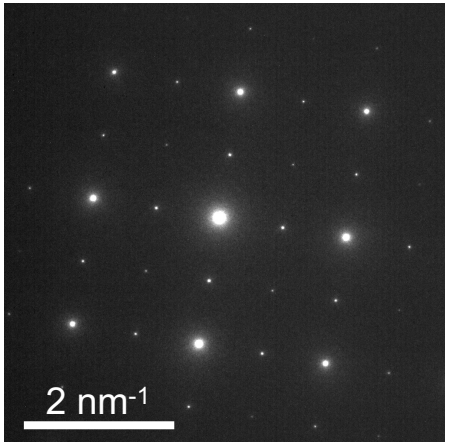
Image formation in TEM

Emad Oveisi

Parallel incident e⁻ beam; $\lambda \approx 0.02–0.03$ Å



Electron diffraction pattern



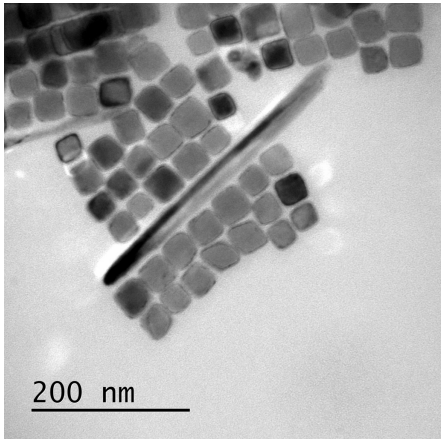
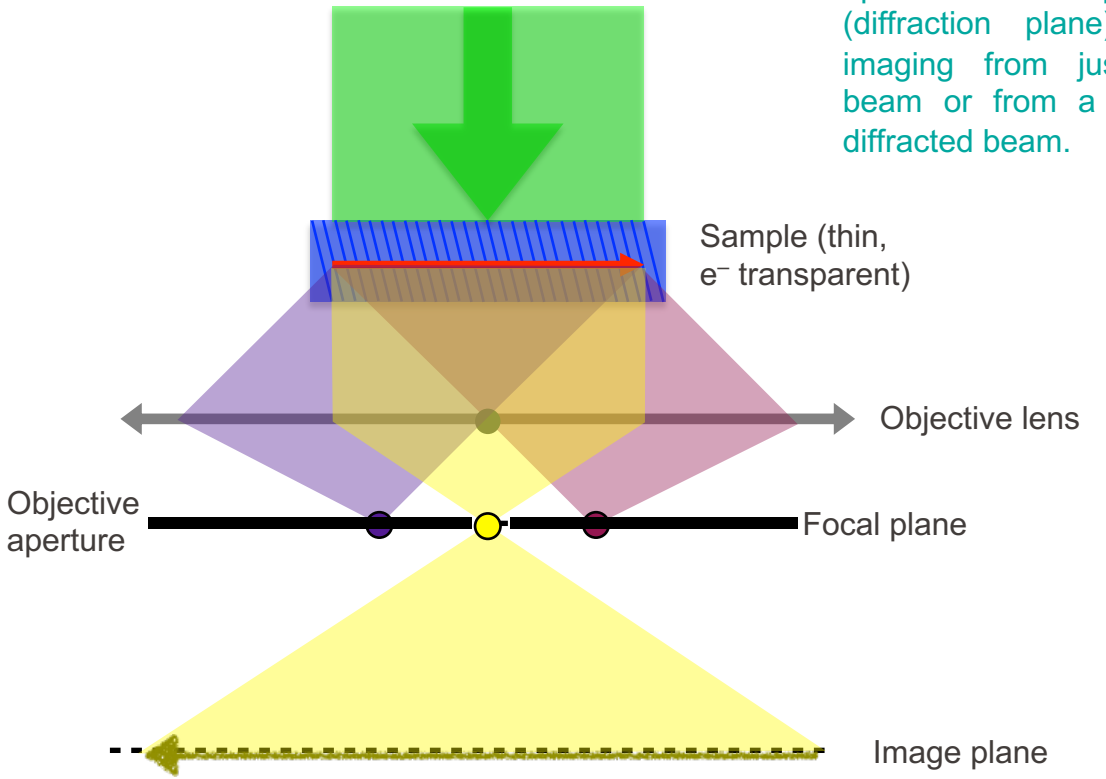


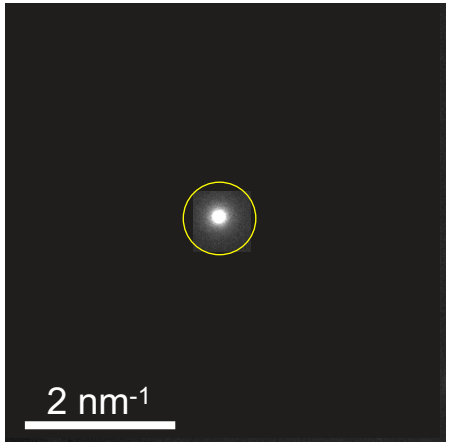
Image formation in TEM

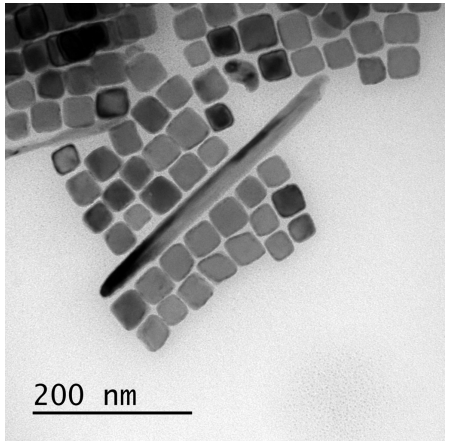
Emad Oveisi



Insertion of the "objective aperture" in focal plane i.e. (diffraction plane) allows imaging from just direct beam or from a selected diffracted beam.

Electron diffraction pattern

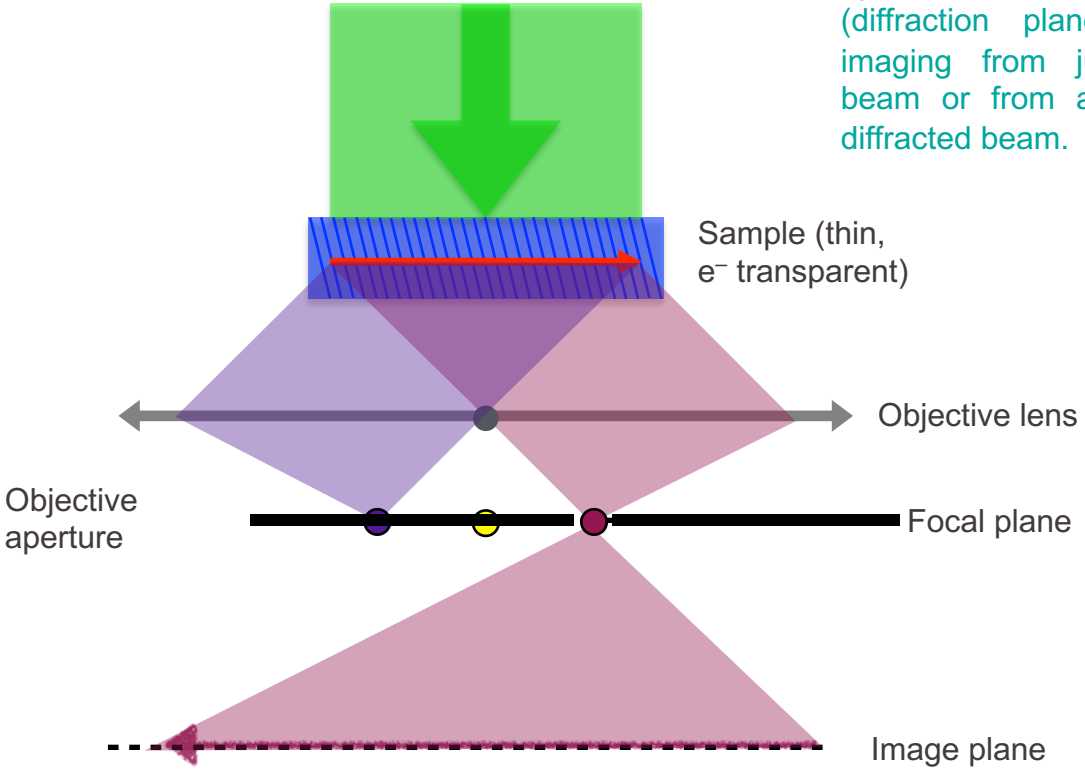




Bright-field image:
made by directly transmitted electrons

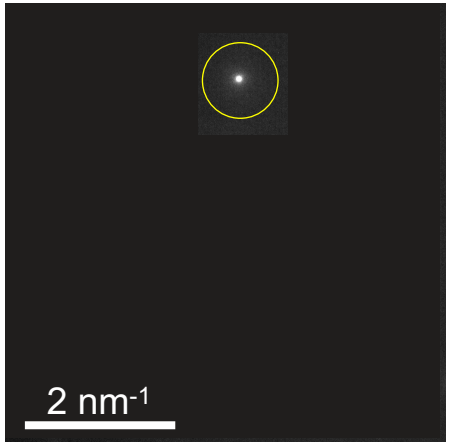
Image formation in TEM

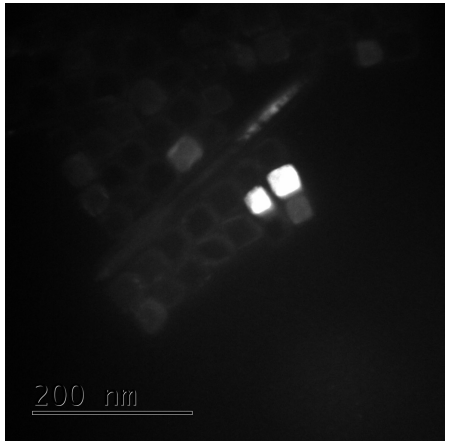
Parallel incident e⁻ beam; $\lambda \approx 0.02–0.03$ Å



Insertion of the "objective aperture" in focal plane i.e. (diffraction plane) allows imaging from just direct beam or from a selected diffracted beam.

Electron diffraction pattern

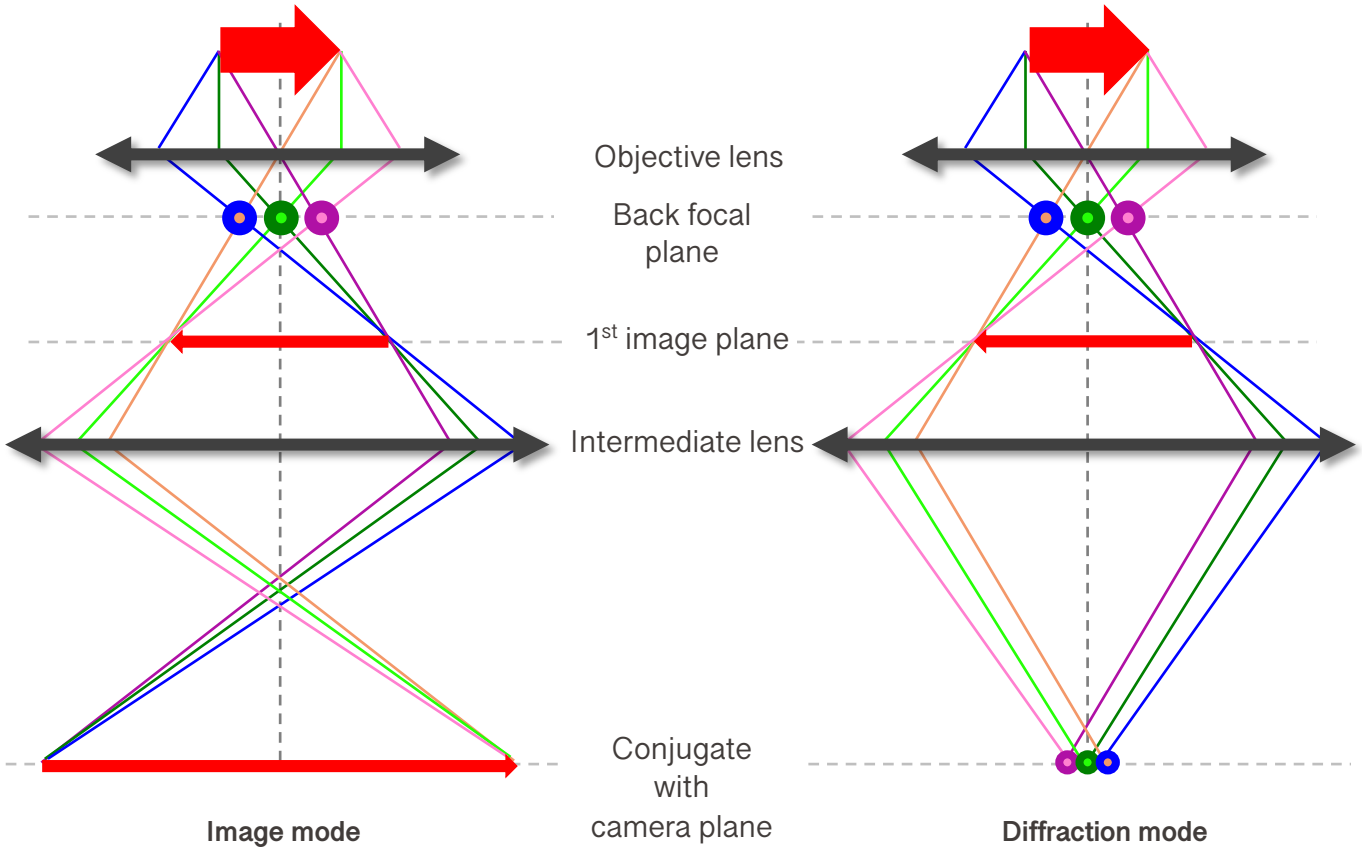




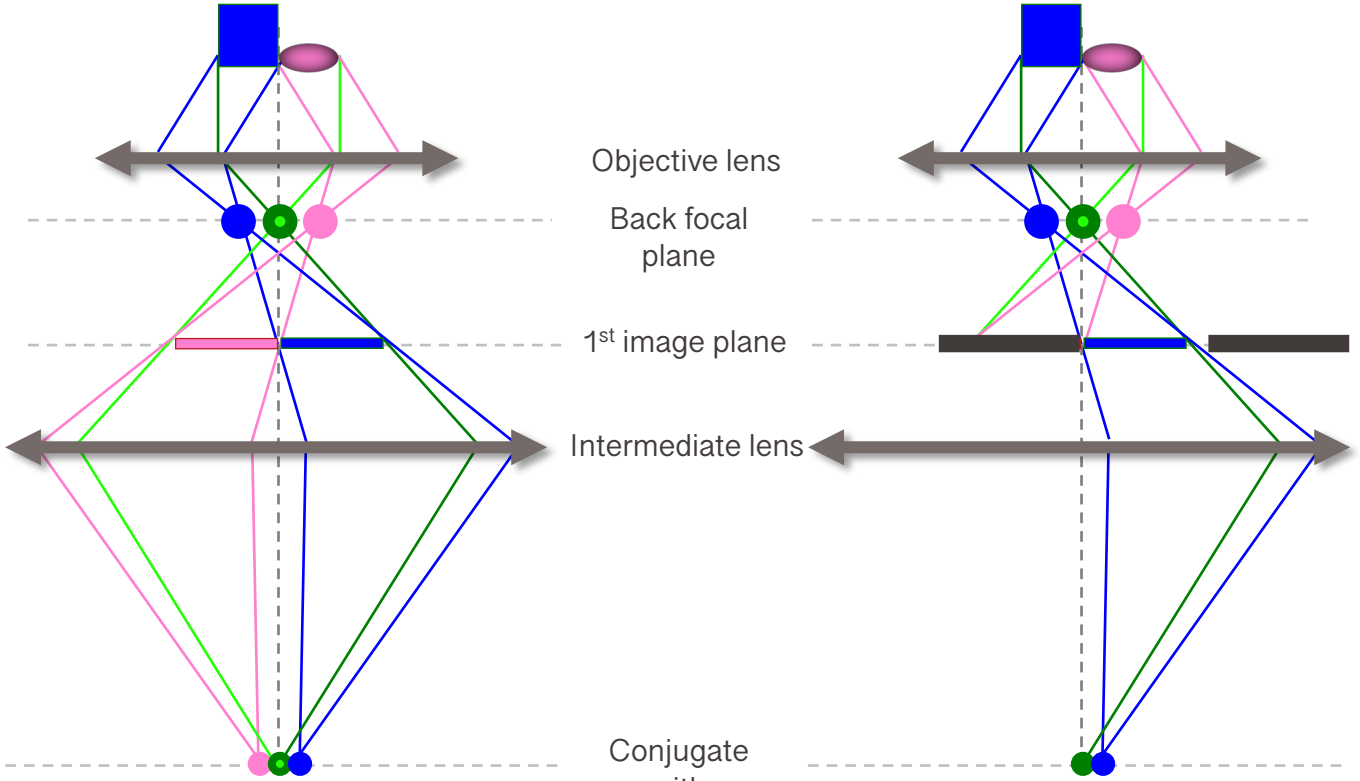
Dark-field image:
made by selected diffracted electrons

Imaging modes in TEM

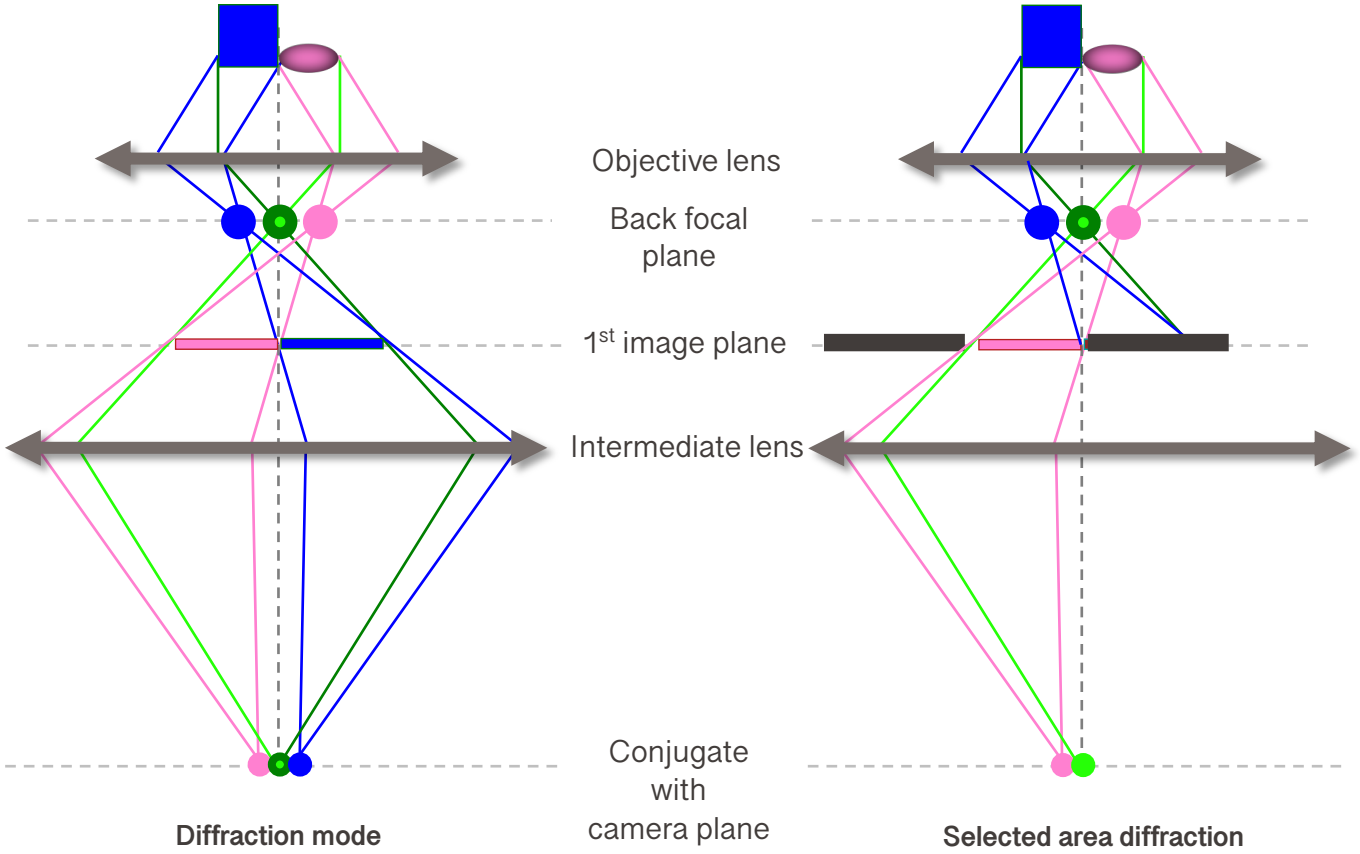
Emad Oveisi



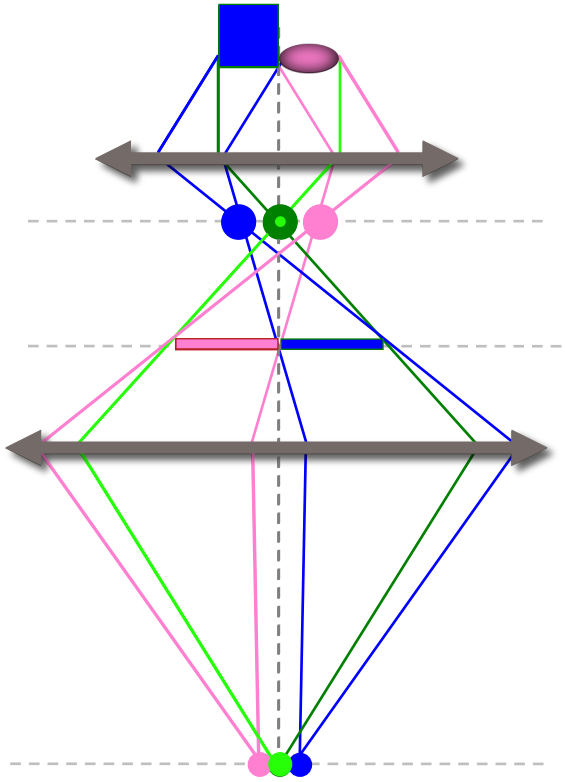
Imaging modes: Selected area electron diffraction



Imaging modes: Selected area electron diffraction



Imaging modes: Selected area electron diffraction



Diffraction mode

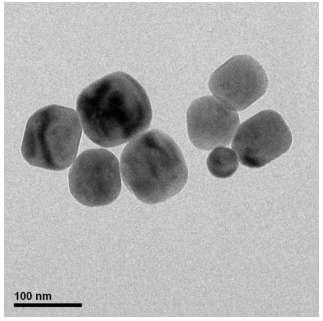
Objective lens

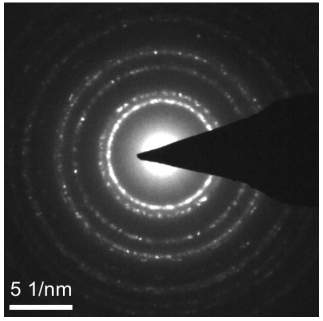
Back focal plane

1st image plane

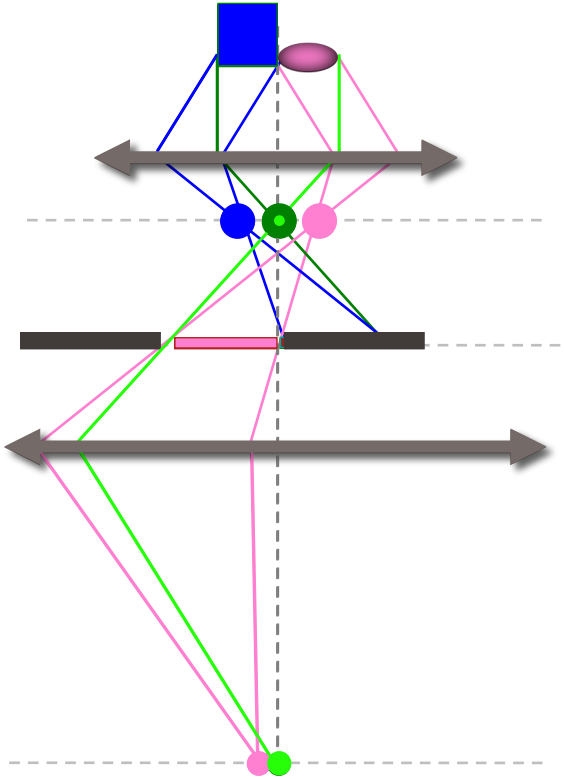
Intermediate lens

Conjugate with camera plane





Imaging modes: Selected area electron diffraction



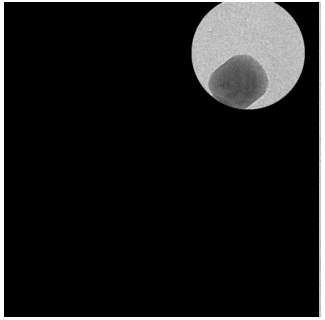
Objective lens

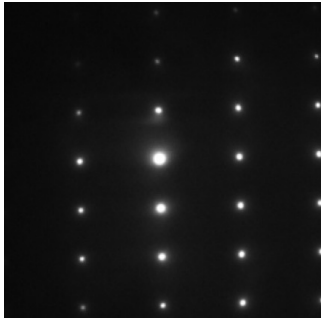
Back focal plane

1st image plane

Intermediate lens

Conjugate with camera plane



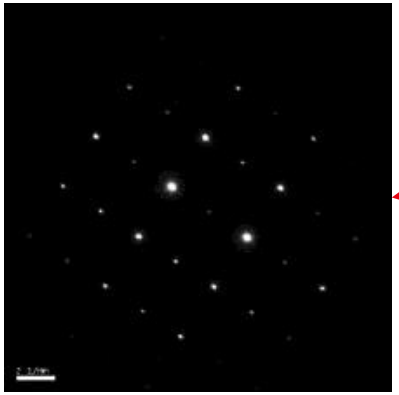


Selected area diffraction

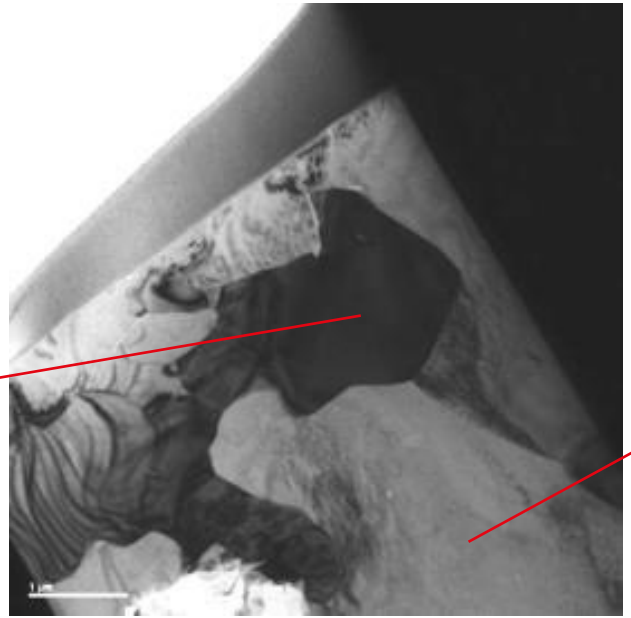
Emad Oveisi

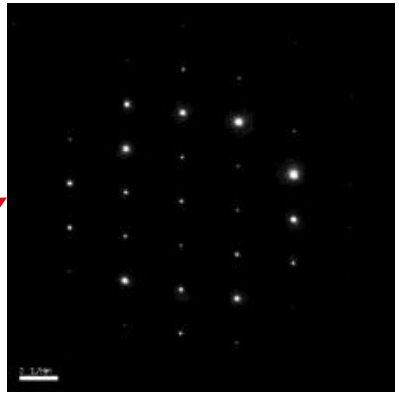
Imaging modes: Selected area electron diffraction

Emad Oveisi



Monoclinic Al_3Fe

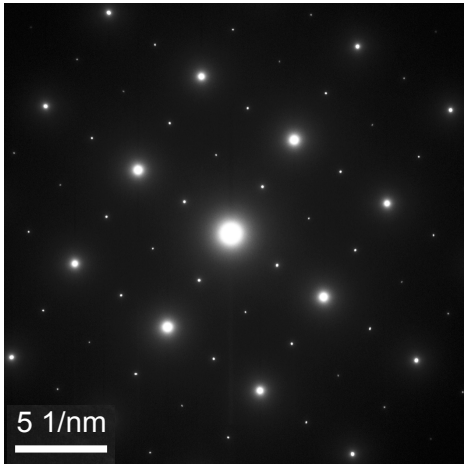




Hexagonal ɣ-(AlFeSi)

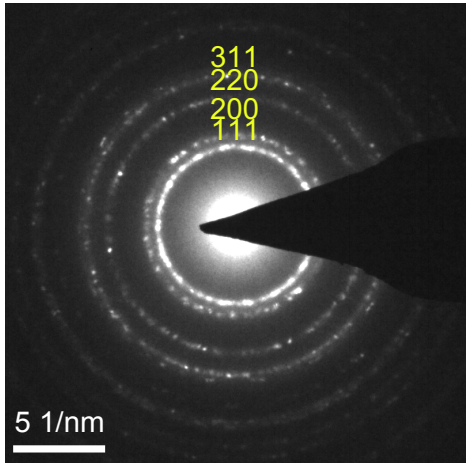
Applications of electron diffraction

Monocrystal



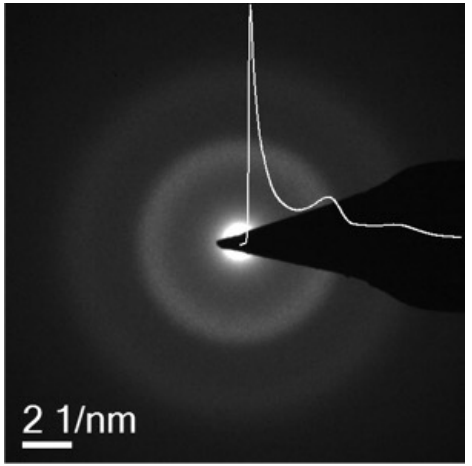
Oriented along a zone axis many (hkl) plans in diffraction conditions. Spot represent different (hkl) planes.

Polycrystalline

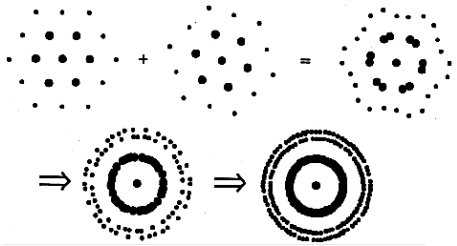


Ring pattern as many crystallites oriented differently in diffraction conditions. Each ring represents one family of {hkl} planes

Amorphous



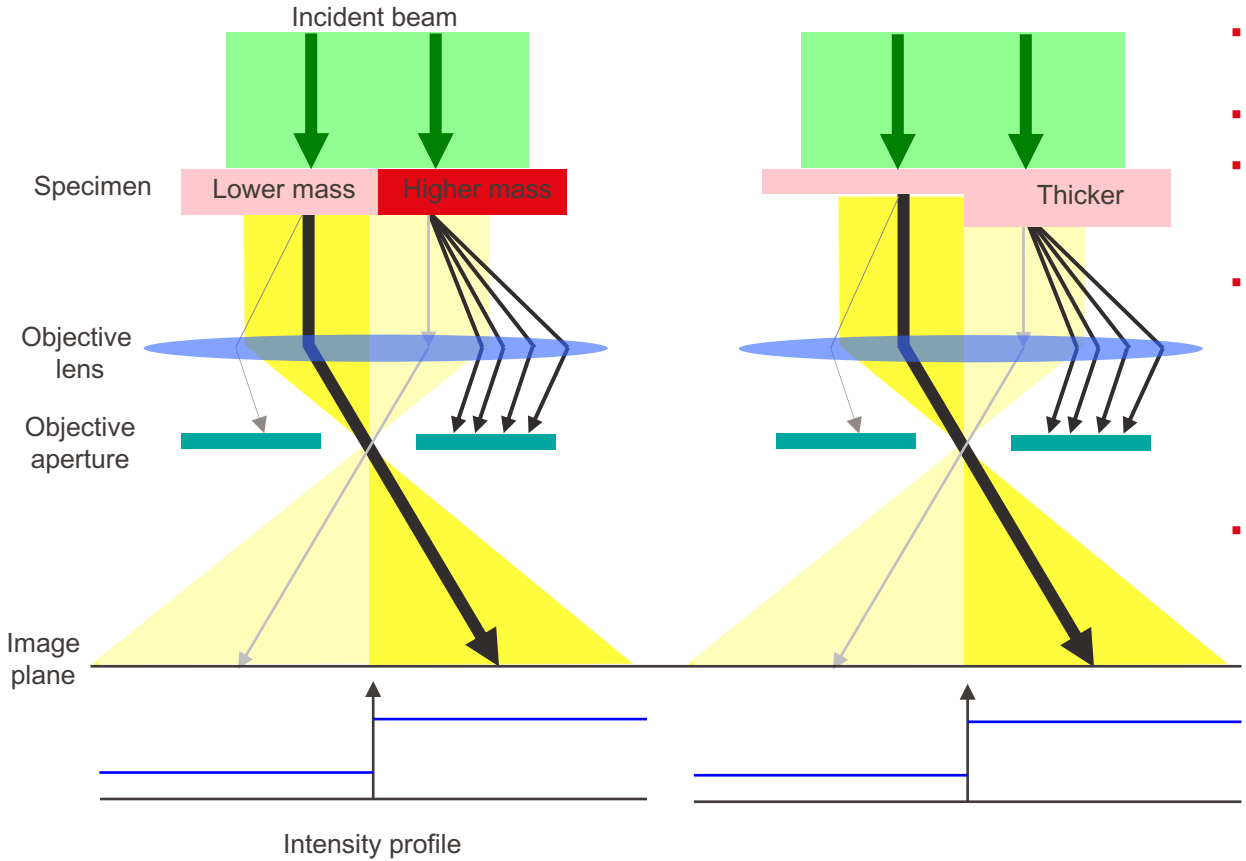
Diffuse ring due to short-range order as interatomic distance ~ constant
Radial distribution function



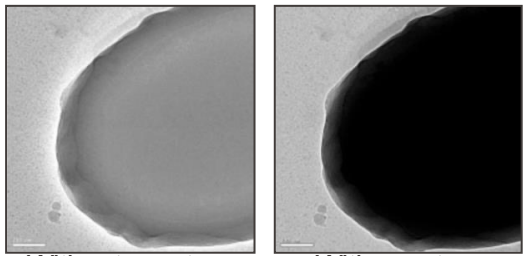
Image/Contrast mechanisms

- **Image formation in TEM**
  - Image and diffraction modes
  - Bright- and dark-field modes
  - High-resolution TEM
- **Image contrast in TEM**
  - Mass-thickness contrast
  - Diffraction contrast
  - Phase contrast

Image/Contrast mechanisms



- Areas of higher mass/thickness scatter electrons more than others.
- Electrons are captured by the aperture.
- Areas of higher mass/thickness will therefore appear dark in the image formed by the direct beam.
- This is known as:
  - **mass thickness contrast**,
  - **scattering contrast**,
  - **aperture contrast** or
  - **amplitude contrast**!
- Applies to both Crystalline and Amorphous materials.

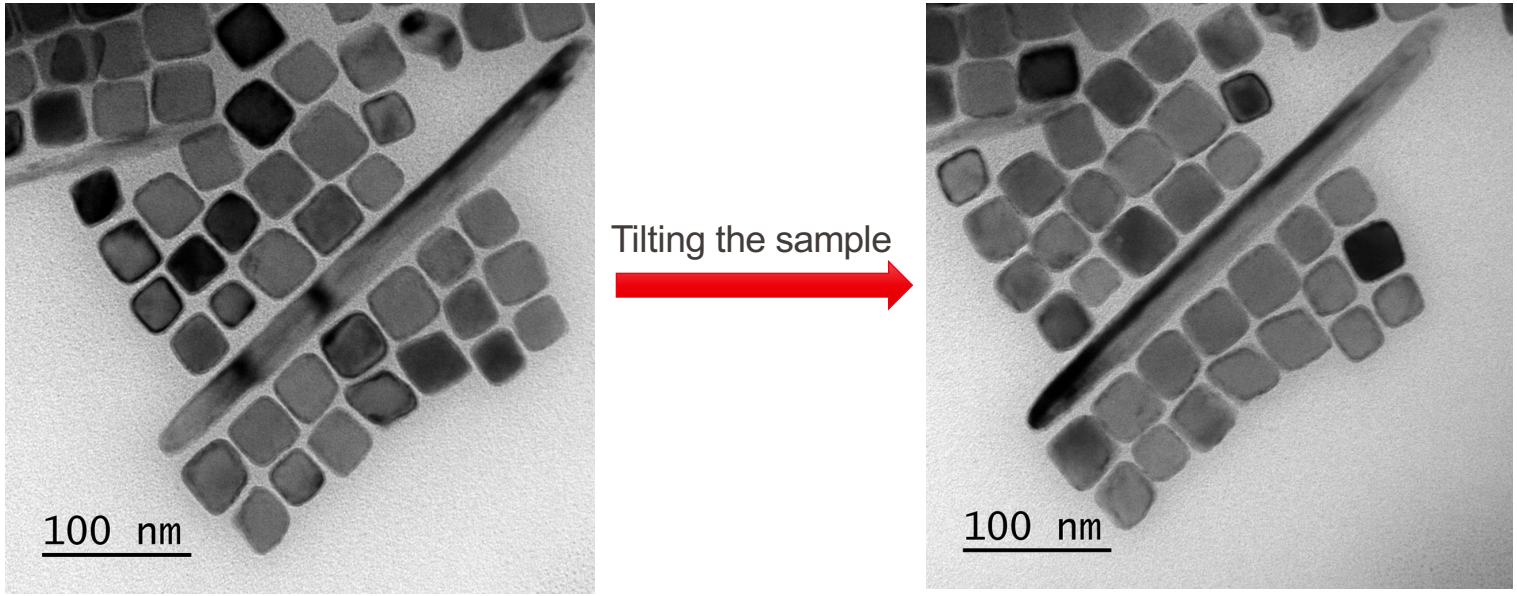


Without aperture | With aperture

Image/Contrast mechanisms

Emad Oveisi

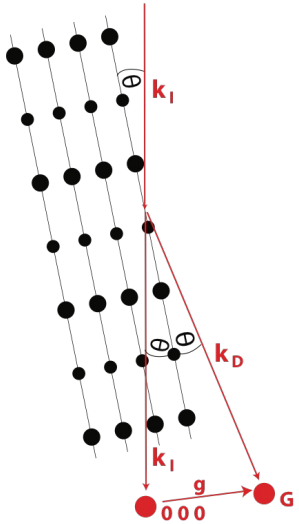
Example: Cupper nano particles



Why some of cubic particles appear darker than others?

Note that contrast changes when tilting the specimen

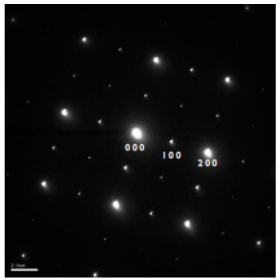
Image/Contrast mechanisms

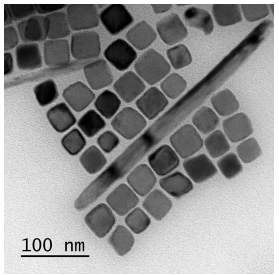


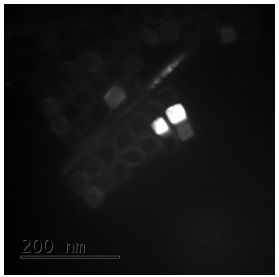
Path difference between reflection from planes distance d_{hkl} apart
$= 2d_{hkl}\sin\theta$

Bragg law: $\lambda = 2d_{nhnknl}\sin\theta$

→ Bragg diffraction at angle 2θ

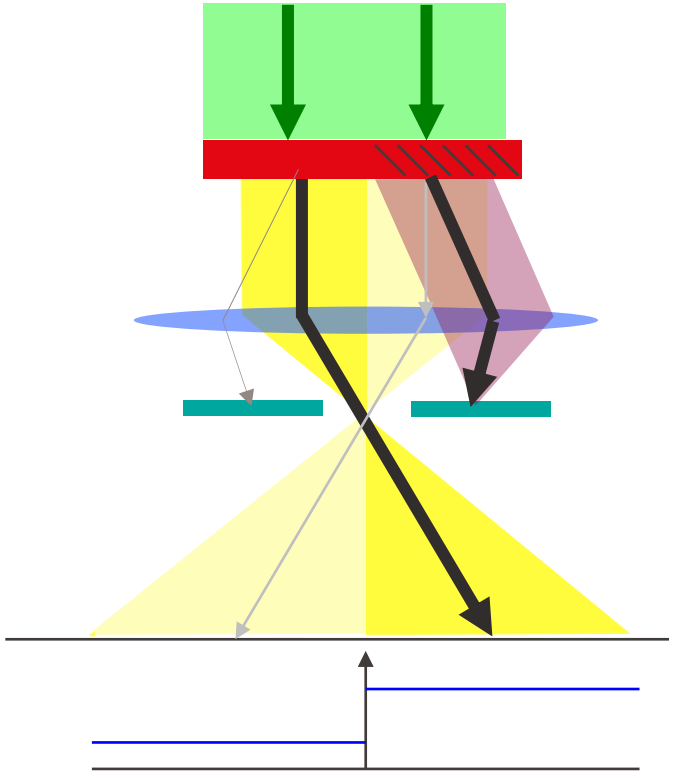






TEM gives image & diffraction information!

Diffraction contrast



Diffraction contrast imaging

Principle of diffraction contrast imaging:

Typically we use an objective aperture to select either the direct beam or a specific diffracted beam in the back-focal plane.

If the diffraction condition changes across the sample the intensity in the selected beam changes; the intensity in the image changes correspondingly.

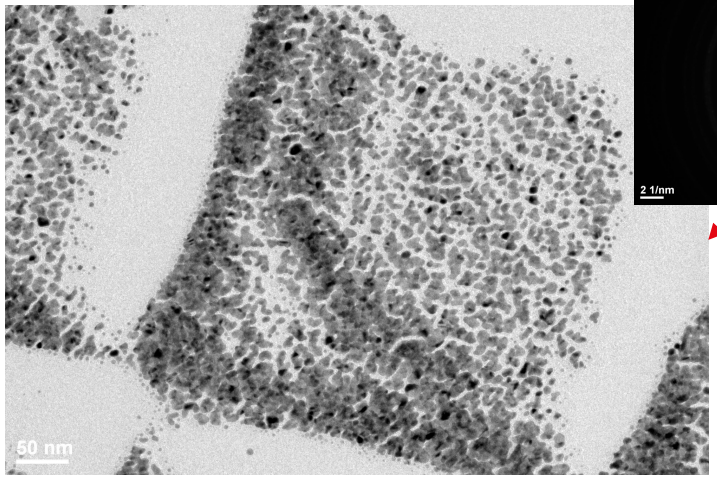
In other words we make a spatial map of the intensity distribution across the sample in the selected beam: *it is a mapping technique.*

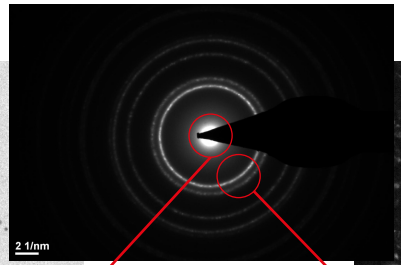
In this way we can image changes in crystal phase and structural defects such as dislocations

As an example such TEM imaging was a key piece of evidence proving the existence of dislocations

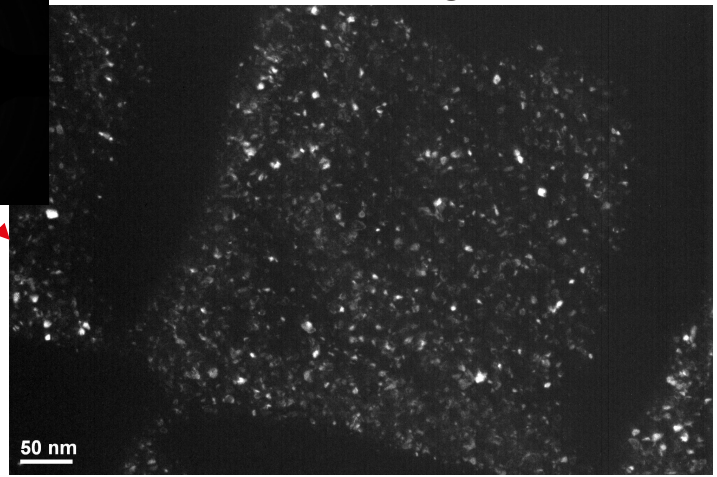
Diffraction contrast imaging

Bright-field image





Dark-field image



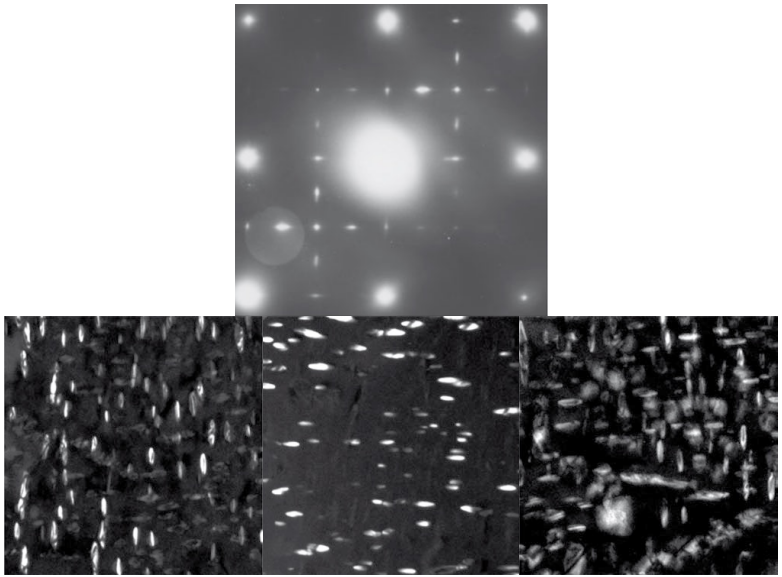
- Strongly diffracting crystals: dark
- Removes ghost image

- Only crystals strongly diffracting into objective aperture: bright
- Possibility of crystal phase/orientation discrimination

Diffraction contrast imaging

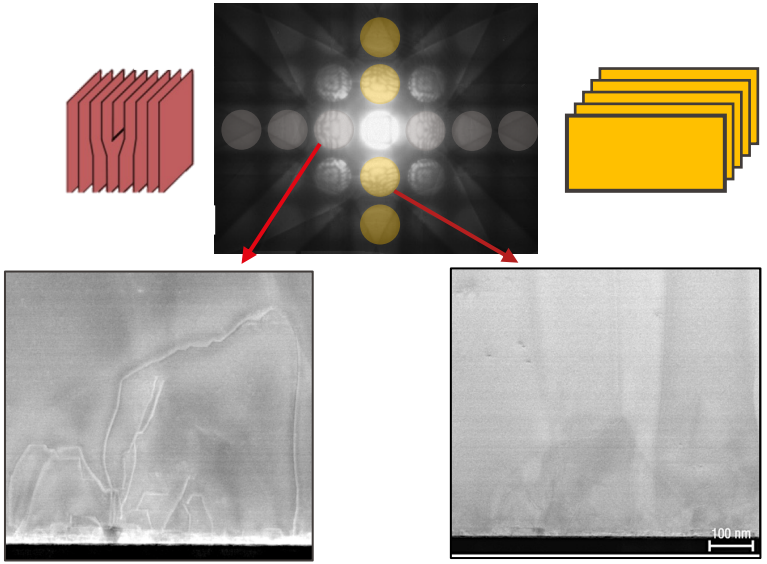
Map intensity in the diffracted beam

Crystal phase/orientation discrimination



Al-alloy containing precipitates with preferential growth direction

Crystal's defect imaging/analysis

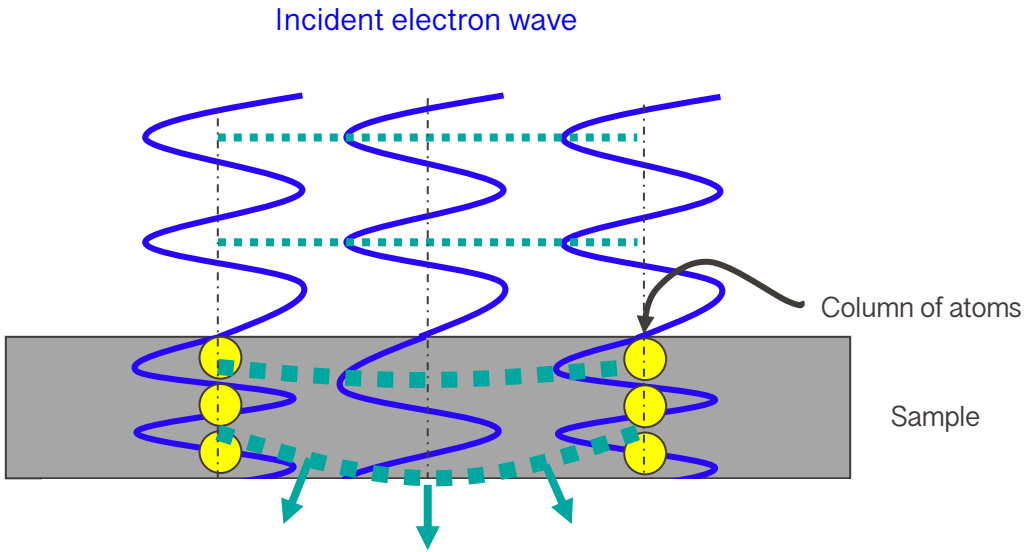


Dark-field images of dislocations in GaN thin film on sapphire

- **Image formation in TEM**
  - Image and diffraction modes
  - Bright- and dark-field modes
  - High-resolution TEM
- **Image contrast in TEM**
  - Mass-thickness contrast
  - Diffraction contrast
  - Phase contrast

Phase contrast | High-resolution TEM

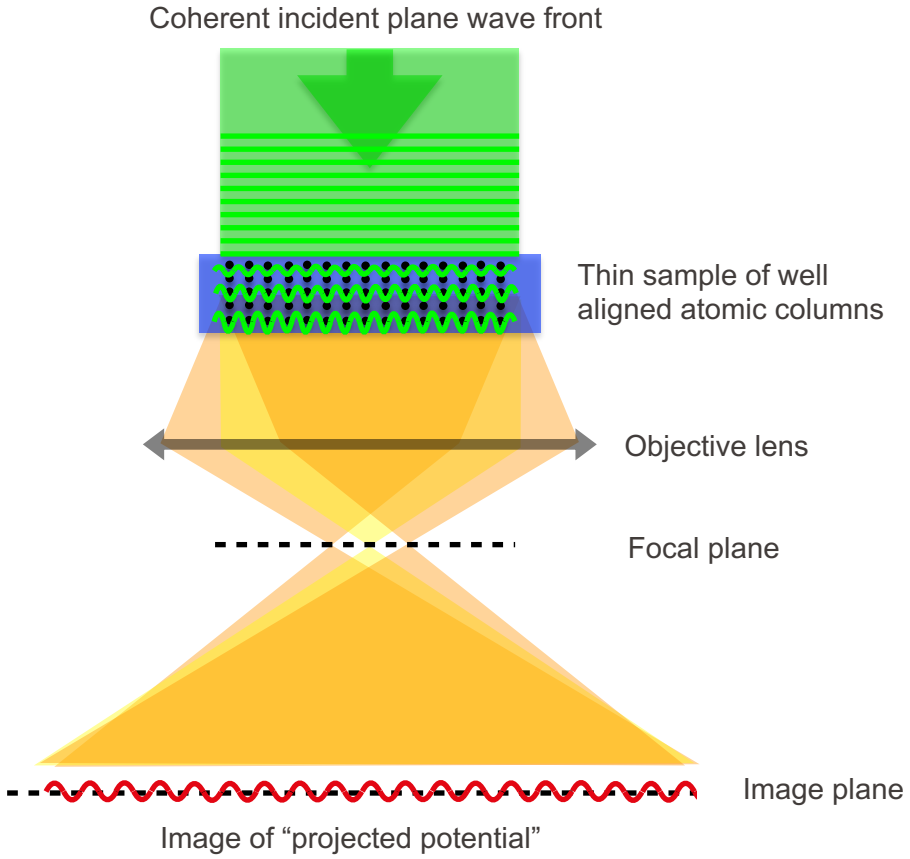
What happens when an electron wave passes through the sample?



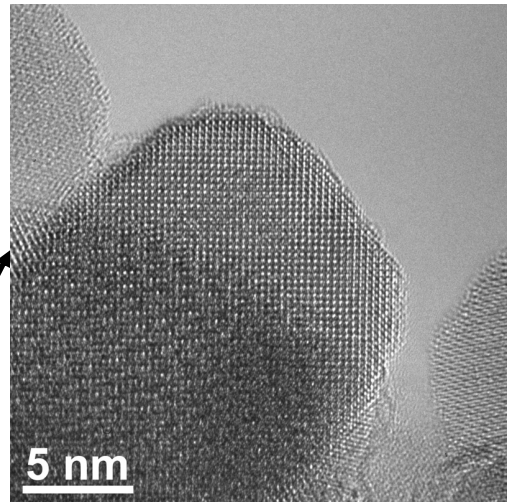
Variations in the projected potential produce local relative phase shifts of the electron wave. The wave front therefore bends as wave travels through medium.

The direction of propagation of the electron may change! ⇒ Diffraction!

Phase contrast | High-resolution TEM



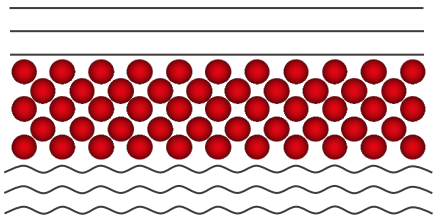
Due to changes in sample thickness and orientation, as well as lens imperfections, image interpretation is complex.

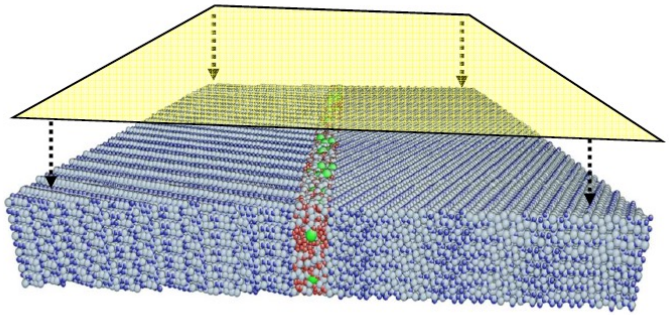


Lattice fringes in iron oxide nanoparticles

Phase contrast | High-resolution TEM

Emad Oveisi





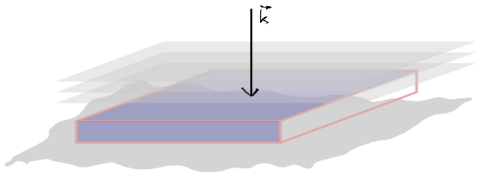
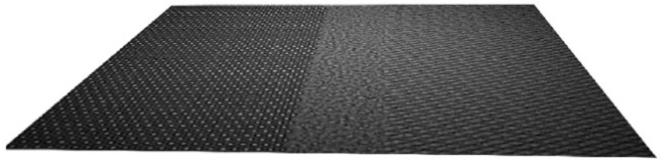


Image forming lens

But …
not a perfect lens!



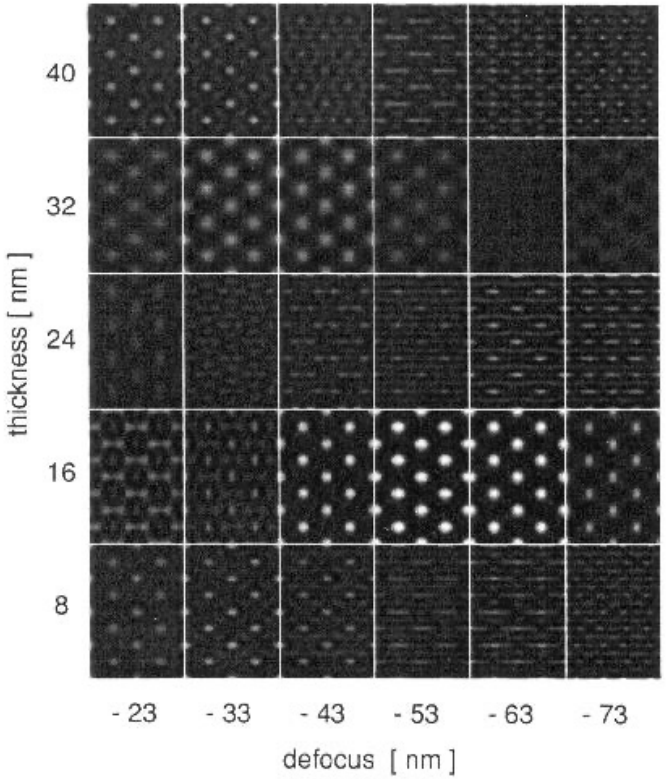
HR-TEM can give you local structural information of your specimen. However, do not expect straightforward interpretation.

Resist the temptation of interpreting the spots as atoms!

Phase contrast images can be difficult to interpret, because many factors contribute to phase shift:
Thickness, orientation, scattering factor, focus, spherical aberration

Schematic from C.T. Koch, QEM's lecture 2013.

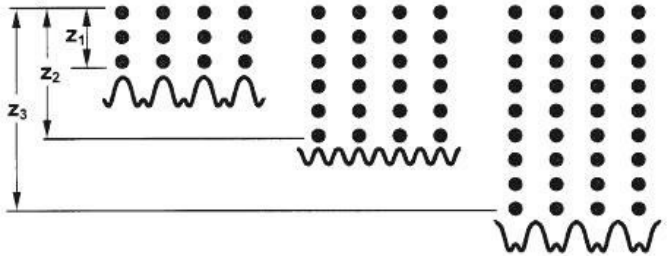
Phase contrast | High-resolution TEM



Resist the temptation of interpreting the spots as atoms!

The crystal potential serves to phase shift the electron wave locally; and crystal thickness affects phase shifts.

Thus at the crystal exit surface, the electron wave carries information about the crystal potential, projected in the direction of the incident beam.



The objective lens (CTF) determines how much phase signal gets transmitted to the real space wave-function in the image plane.

Miroslav Karlík, Materials Structure, 8 (2001) 3

More details in MSE637

Summary

Mass-Thickness contrast

- Applies for both crystalline and amorphous phase

Diffraction contrast

- Bright-field: objective aperture centered on “unscattered” beam
- Dark-field: objective aperture centered on “diffracted beams”

HR-TEM Phase contrast

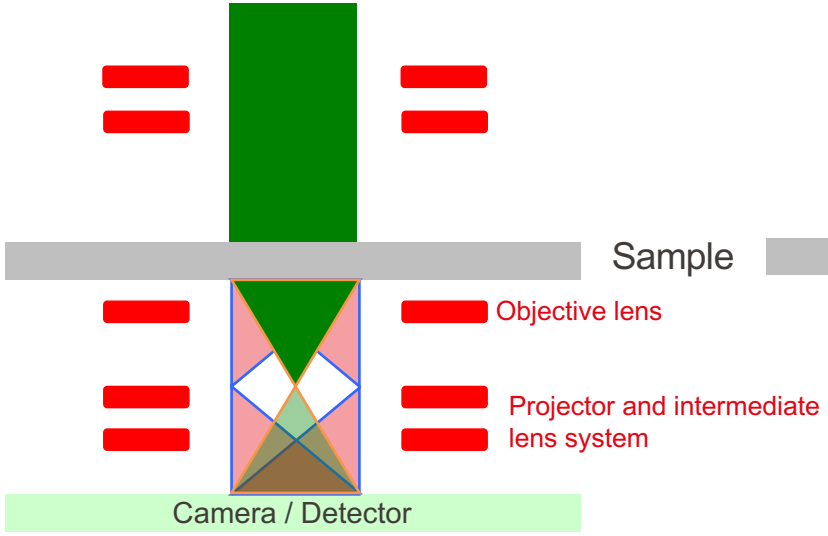
- Developed by the interference of two waves, one which undergoes a phase shift due to the interactions with the sample crystal structure of a given thickness and is altered by the microscope aberrations
- Simulations are needed to interpret phase contrast images properly

TEM operation modes

Emad Oveisi

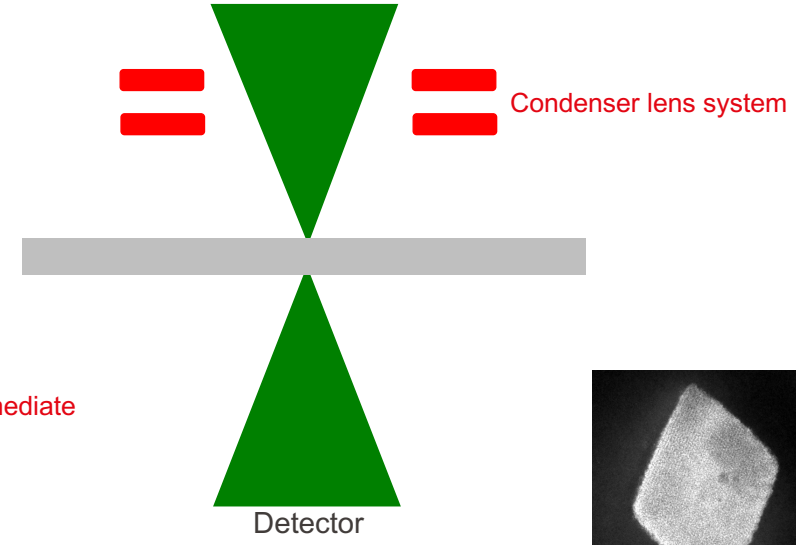
Conventional TEM

Electron beam (60-300 keV)



Scanning mode (STEM)

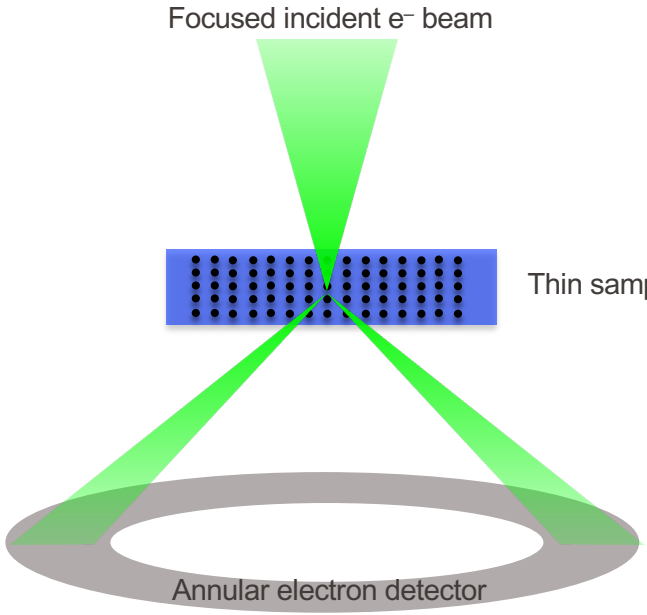
Electron beam (30-300 keV)

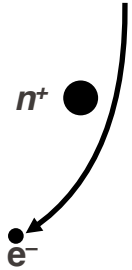


Fe-based metal-organic framework

2D projection of a 3D object

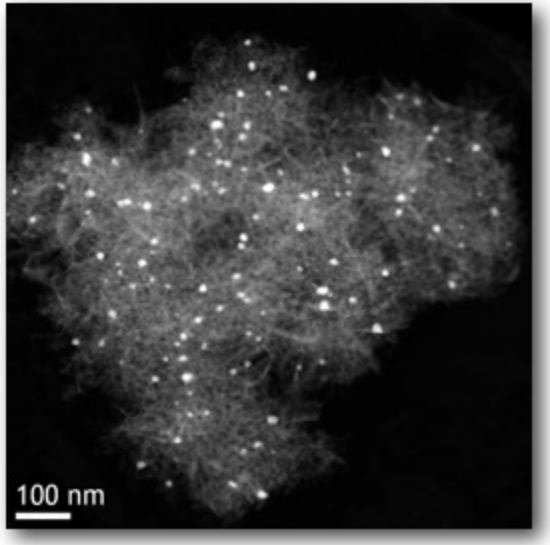
Scanning TEM (STEM) with focused probe





Rutherford-type scatteringcfrom nucleus (thermal diffuse scattering)

High-angle annular dark-field (HAADF) image



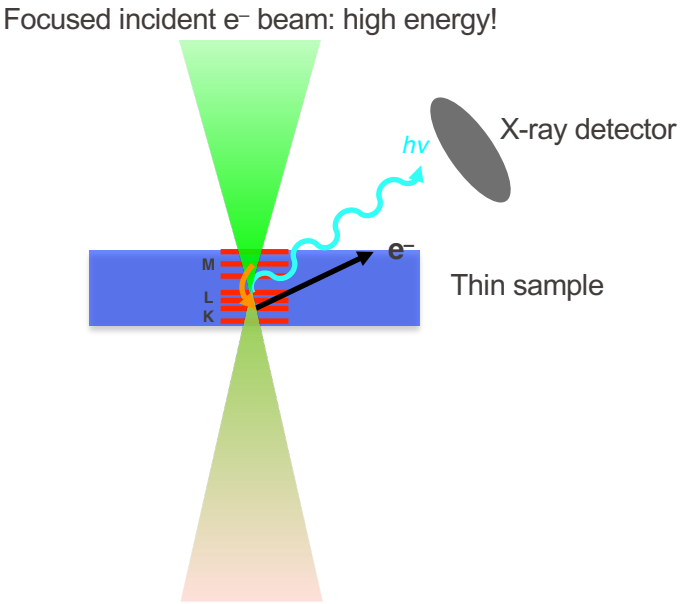
Pt catalyst particles on Al_2O_3

Mass/thickness contrast image

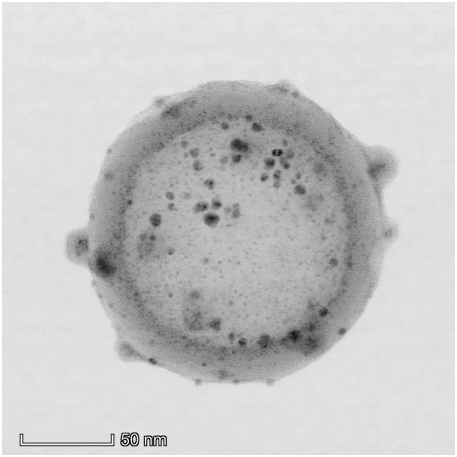
- Incoherent Rutherford-type scattering deflects transmitted e⁻ to high angle of scattering
- Larger nucleus / thicker the specimen → More scattering
- Map image intensity as function of probe position *(x, y)*
- Image intensity: $I(x, y) \propto t * Z^{1.6–2}$

Emad Oveisi

Ionisation and energy-dispersive X-ray (EDX) mapping

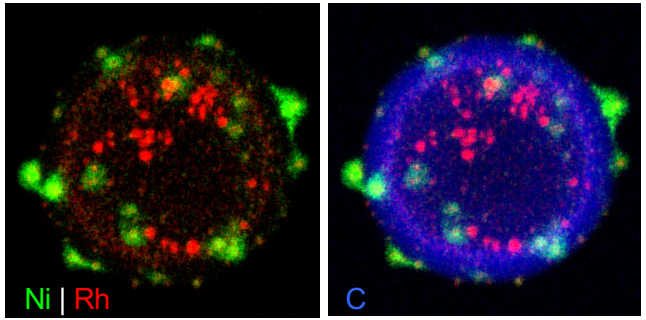


Transmitted beam suffers energy loss → Used in EELS



Ni-Rh catalytic nanoparticles in carbon shell

- High energy incident electrons (ballistic) → Ejection of inner shell e⁻
- Upper shell e⁻ descends
- Transition energy emitted as X-ray;
  Characteristic of element | $E_{X\text{-}ray} = E_{Upper\ shell} - E_{Inner\ shell}$



Map X-ray intensity as function of probe position (x,y)

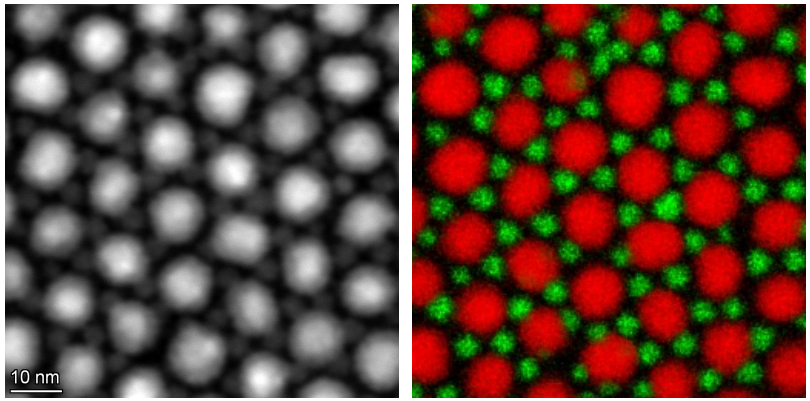
STEM-EDX

With fast mapping STEM-EDX has become a regular feedback tool for materials synthesis

Sample characterized in a couple of minutes/hours

With aberration-corrected STEM, atomic resolution EDX became possible

Example : Assembly of Fe_3O_4 and Cu particles



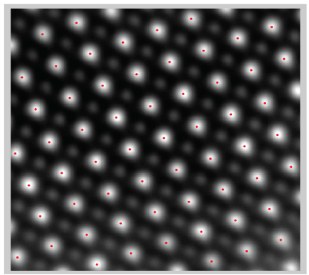
HAADF image

Map of Cu and Fe

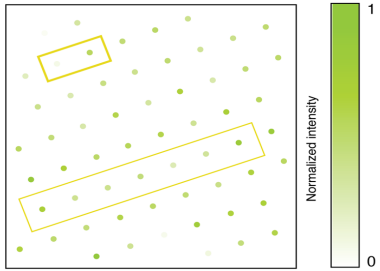
In collaboration with Chethana Gadiyar LNCE, EPFL

J. Am. Chem. Soc. 2020, 142, 37, 15931–15940

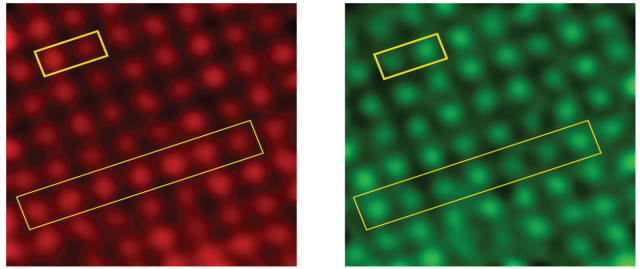
Example: $(Ba_xSr_{1-x})TiO_3$



HAADF image



Intesnsity map

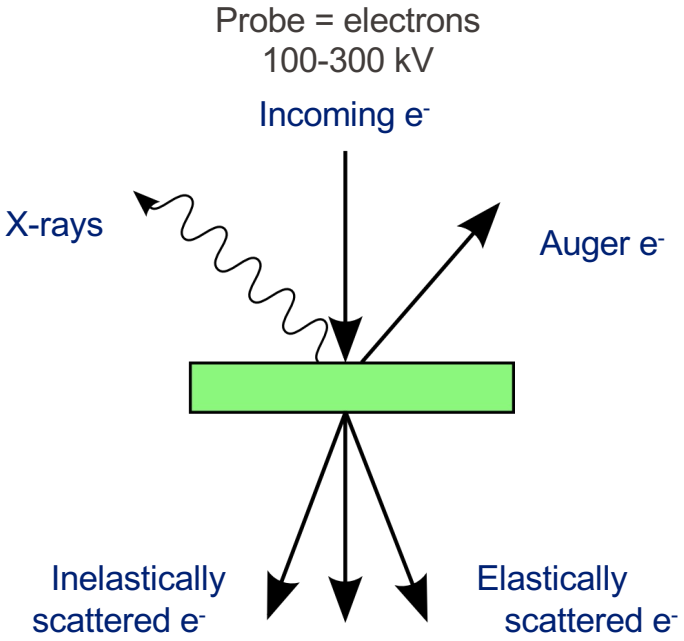


Map of Sr and Ba

In collaboration with Prof. Dragan Damjanovic, EPFL

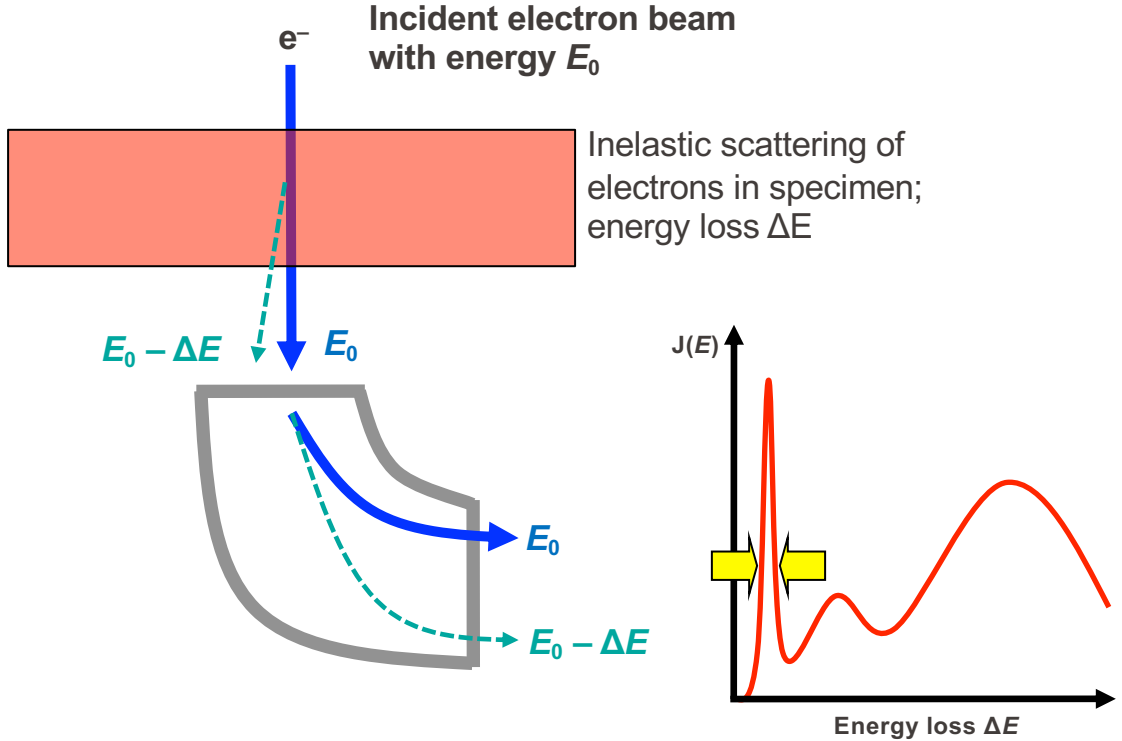
Electron energy-loss spectroscopy (EELS)

The TEM specific microanalysis technique!



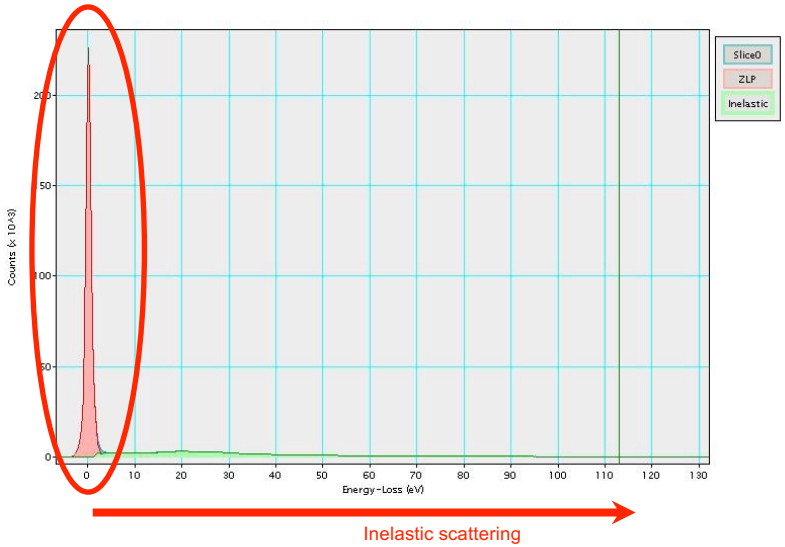
Principle of EELS

e.g. Gatan Enfina



Magnetic prism separates electrons with different energy; produces spectrum of intensity J(E) vs energy loss ΔE: **The energy-loss spectrum**

The EELS spectrum | Zero loss



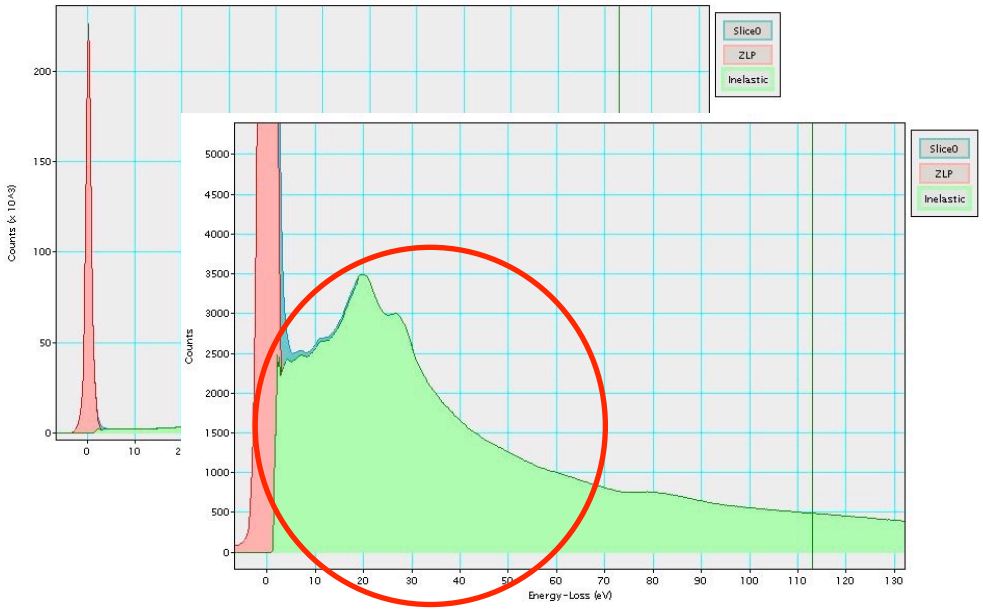
Zero-loss: Elastically-scattered e^-

Information about speciemen thickness

Emad Oveisi

The EELS spectrum | Low-loss

Emad Oveisi

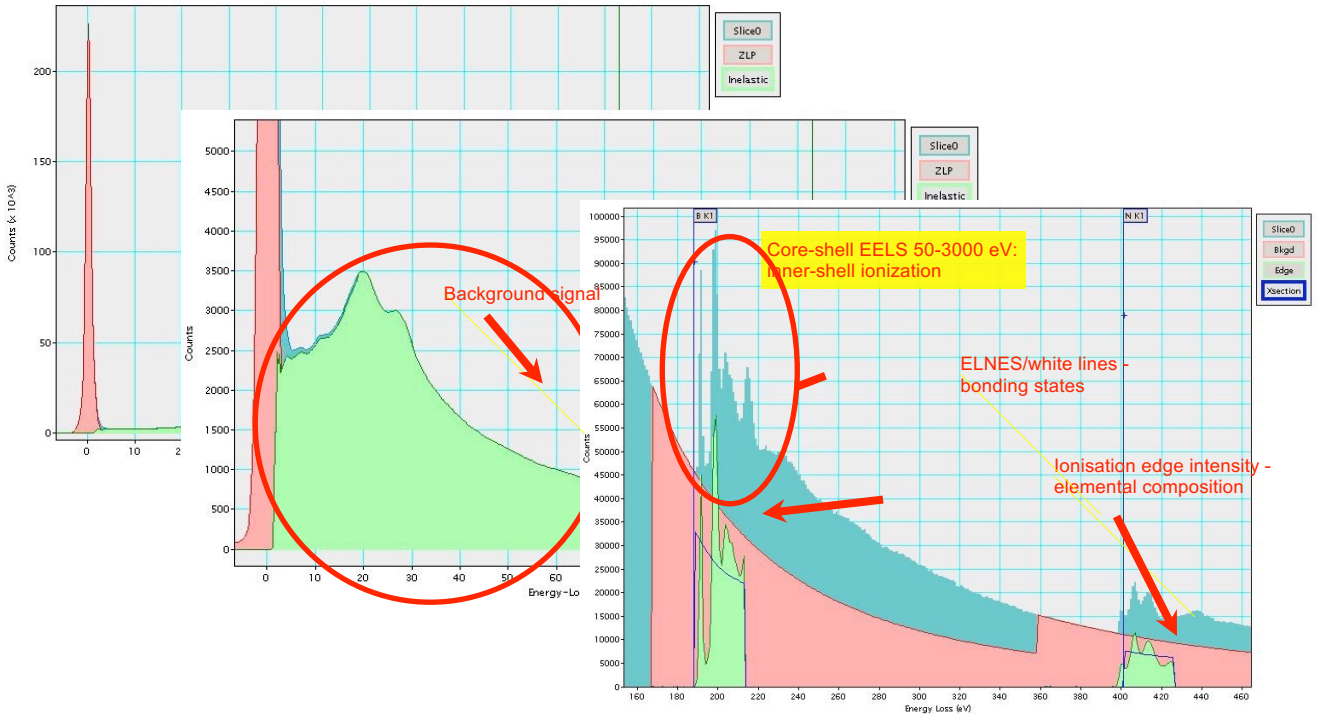


Interaction with outer electrons (conduction/valence)

Low-loss spectrum 0-50 eV: valence excitations - plasmons (bulk & surface),
band gaps, optical properties

The EELS spectrum | Core-loss

Emad Oveisi

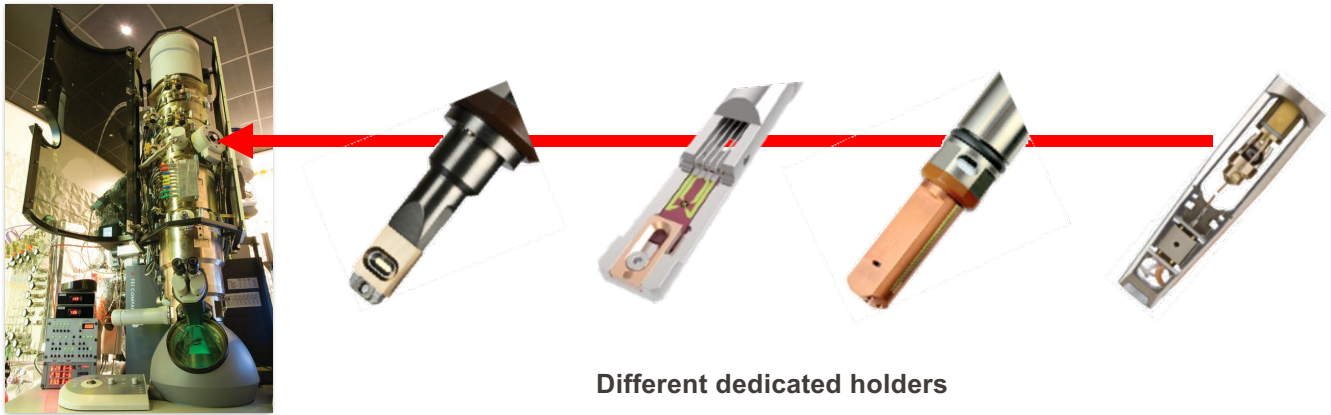


Interaction with core electrons

Core-loss spectrum 50-3000 eV: inner shell ionization
ELNES/white lines: Bonding state
Ionisation edge intensity: elemental composition

In situ TEM

Stimuli	Possible techniques	Information
• gas • liquid • temperature • magnetic field • current/voltage • mechanical load • light • …	• (S)TEM imaging • diffraction • electron energy-loss spectroscopy • energy-filtered TEM • energy-dispersive X-ray spectroscopy • Lorentz microscopy • holography • …	• microstructure • crystallography • chemistry • diffusion/migration • optical properties • electric fields • magnetic fields • …



Different dedicated holders

In situ TEM

Liquid phase processes
Hydration and other liquid phenomena
Crystal growth from the liquid phase
Corrosion

Phase transformations
Solid state phase transformations
- Crystallization and melting
- Structural transformations
- Solid state reactions

Solid state transformations in nanostructured materials
- Size-dependent transformations in embedded nanoparticles
- Shape and phase transformations in free-standing nanoparticles
- Sintering of nanoparticles

Elastic and plastic deformation
Microscopic phenomena during plastic deformation
- Deformation of polycrystalline materials
- The effect of gas environment on deformation
- Grain boundary motion
- Deformation phenomena in single crystals
- Deformation of multilayers

Relaxation of epitaxially strained materials
Mechanical properties of nanostructures, thin films and surfaces
- In situ indentation and straining of thin films
- Mechanical properties of nanostructures
- Surfaces: Tribology and Nanomanipulation

Surface reactions and crystal growth
Modification of surface structure
Oxidation and other chemical reactions at surfaces
Growth of nanostructures
- Carbon nanotubes

Thin film growth and defect formation
- Epitaxial growth
- Polycrystalline growth

Crystal growth on patterned substrates

Domain wall motion and flux dynamics
Magnetic domain switching
Flux motion in superconductors
Switching phenomena in ferroelectrics

Correlation of structural and electronic properties of materials
Electrical measurements on TEM samples: samples as devices
Electrical measurements on individual nanostructures

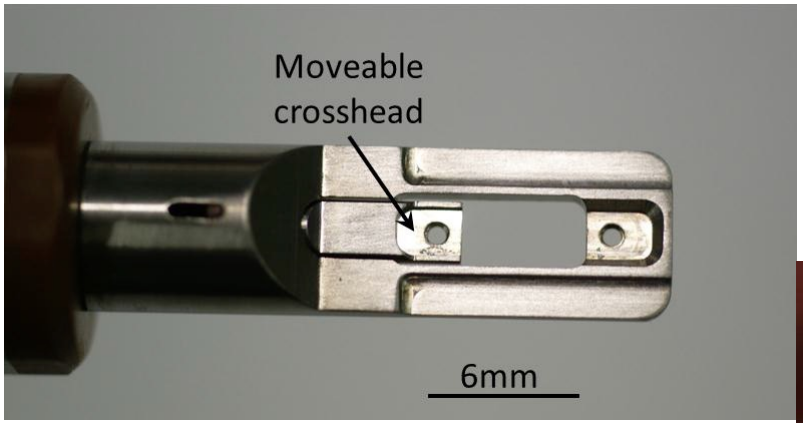
Beam induced processes
Electron beam induced phenomena
- Interaction with the vapour above the specimen
- Formation of point defects
- Beam induced transformations, surface reactions, growth
- Radiation enhanced dislocation motion

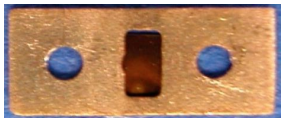
Hole drilling
Ion implantation
- High energy ion accelerators
- FIB in the TEM

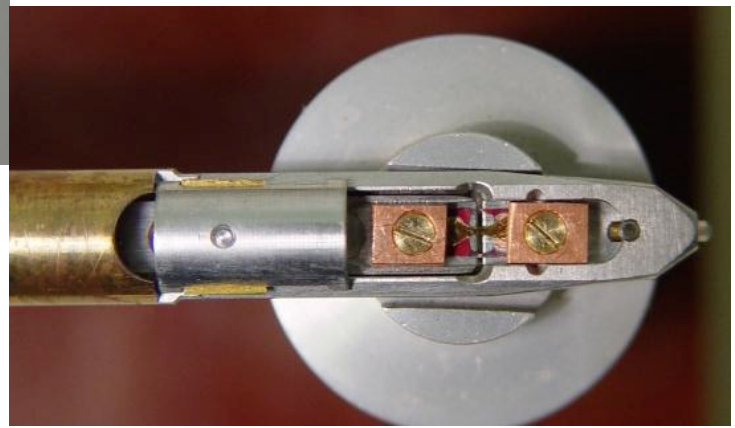
Science of Microscopy, ed. Hawkes and Spence, 2006

In situ TEM straining, deformation, mechanical manipulation

Conventional straining holder







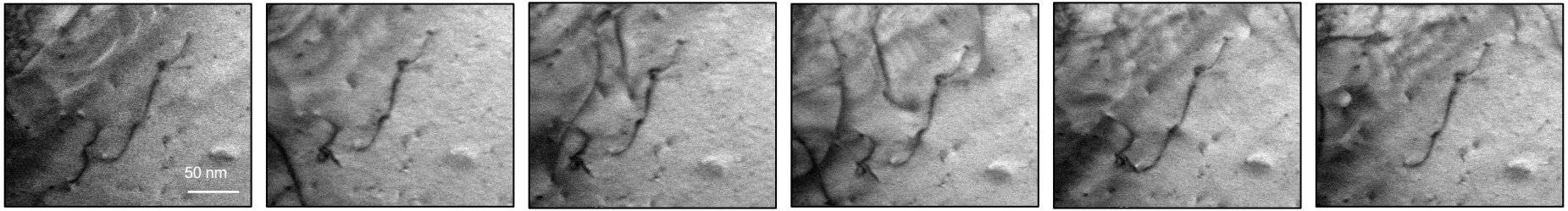
In situ TEM straining experiments: Recent progress in stages and small-scale mechanics, G. Dehm, M.Legros, D. Kiener, Chapter 10 of “In-situ Electron Microscopy“.

In situ TEM straining, deformation, mechanical manipulation

Emad Oveisi

Dislocations interaction

Specimen: Cu foil | *in situ* deformation

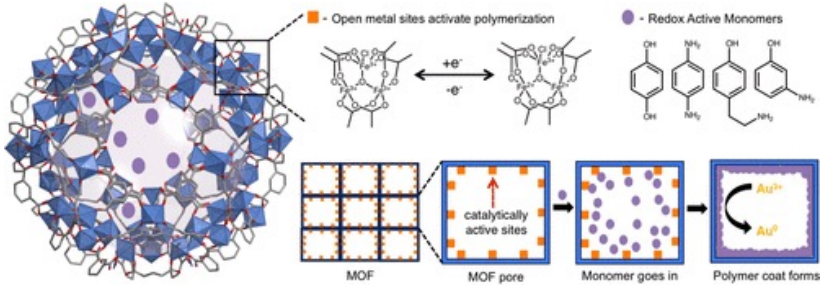


In collaboration with Dr. Marc Legros of CNRS-CEMES Toulouse, France

In situ TEM: Advantages and limitations

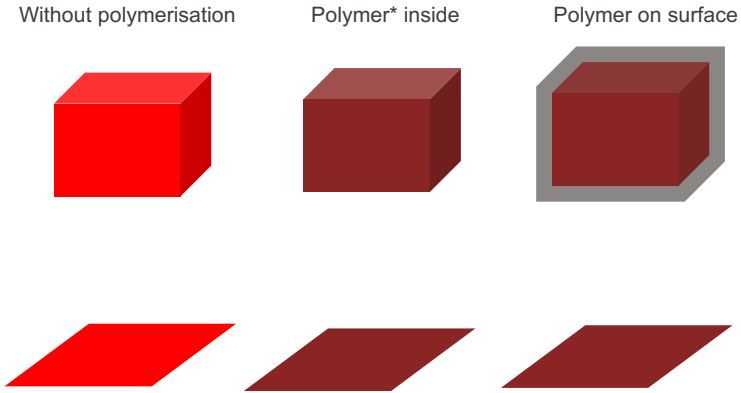
- A window into the behavior of materials under real processing conditions.
- A continuous view of a process, which may take the place of multiple post-mortem measurements.
  - It is easier to catch a transient phase or observe a nucleation event.
  - Specific and detailed kinetic information, such as the motion of individual dislocations under known stress, or growth rates of individual nanocrystals.
- But this unique information comes at the cost of increased experimental complexity.
- Expensive: machine time, holders

Heavy metal removal by Metal-Organic Frameworks



MOF: Fe-BTC

*Para-phenylenediamine (pPDA)



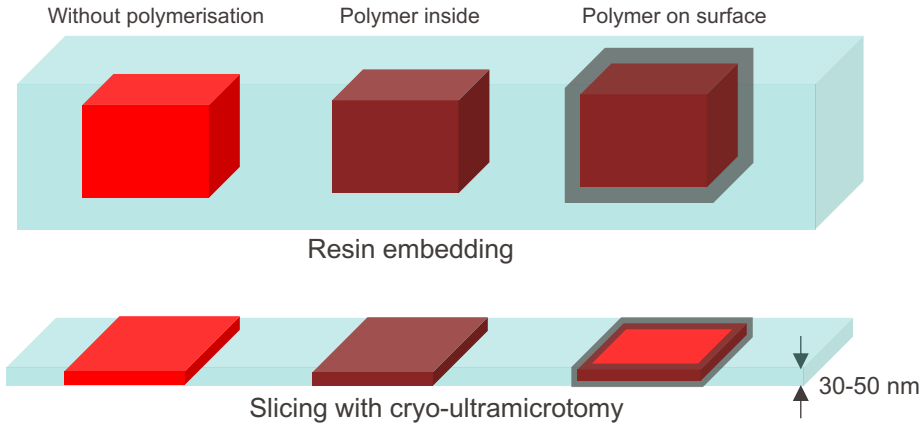
Due to projection problem,
not possible to determine whether the polymer is inside the particle or on its surface

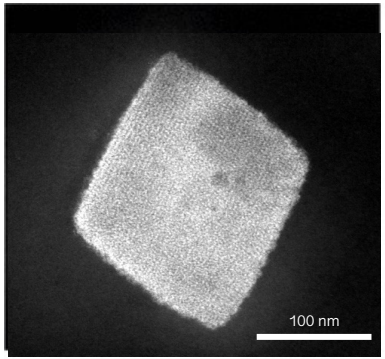
- Collaboration with group of Prof. Wendy Queen, EPFL

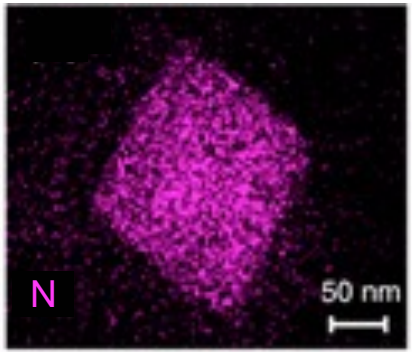
D. Sun, ACS Cent. Sci. 2018.
D. Sun, J. Am. Chem. Soc. 2018.

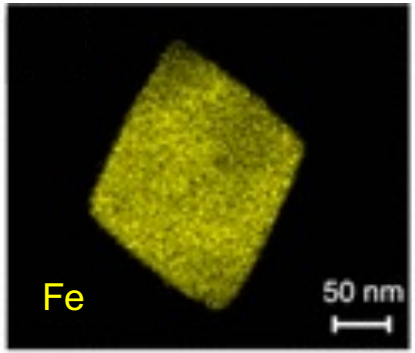
Heavy metal removal by Metal-Organic Frameworks

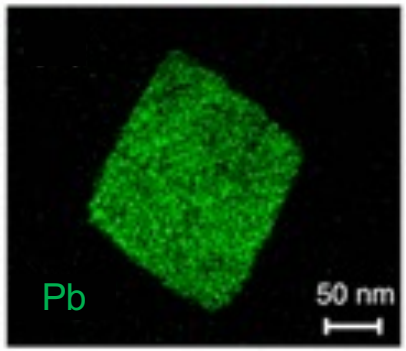
Emad Oveisi





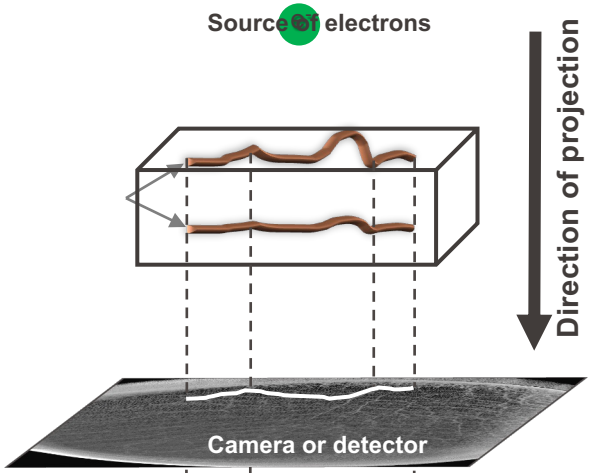




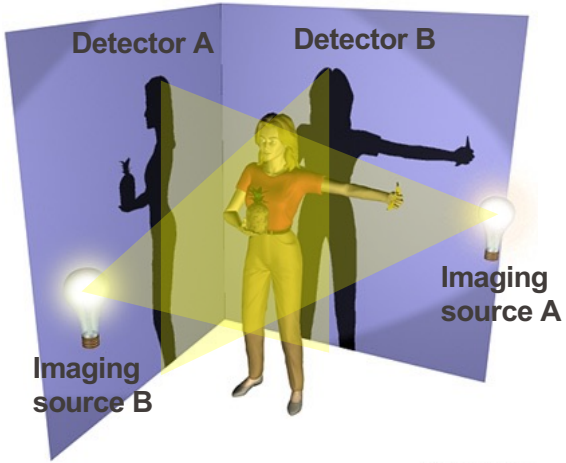


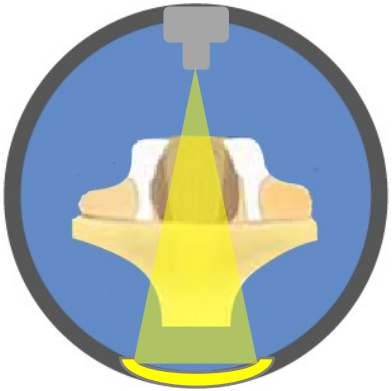
D. Sun, ACS Cent. Sci. 2018.
D. Sun, J. Am. Chem. Soc. 2018.

Projection problem

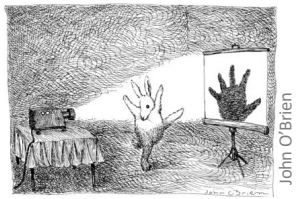


2D image





X-ray Computed tomography (CT) scan

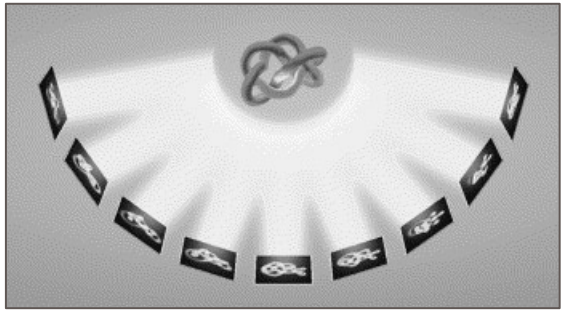


John O'Brien

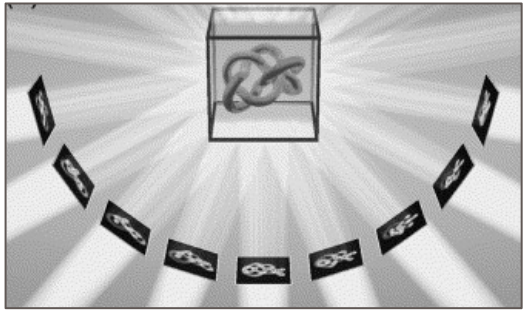
Image is the projection of a 3-D object onto a 2-D plane

Projection problem | 3D imaging in TEM

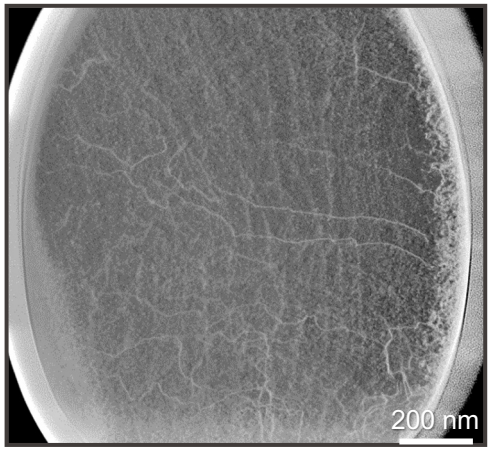
Emad Oveisi



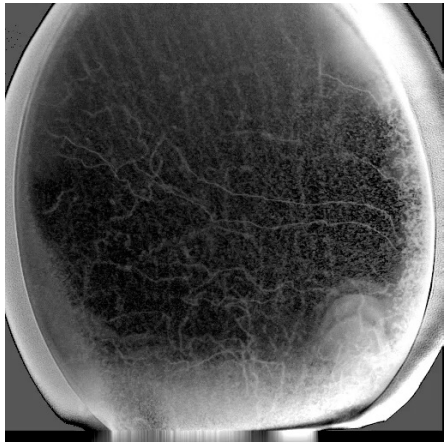
Series of projections



Back-projection

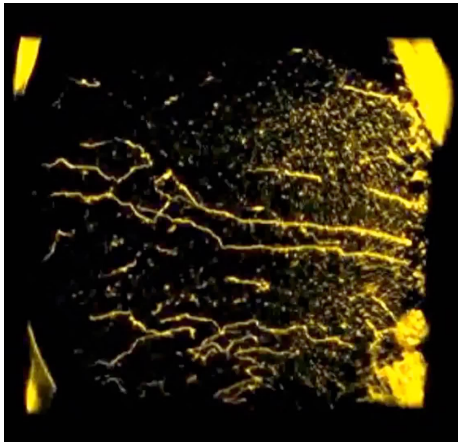


2D image



Series of tilted images

-35°/+35° tilt arc | 1° interval

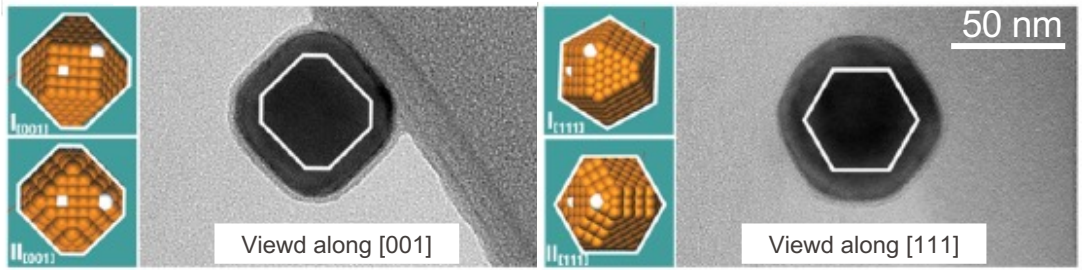


3D reconstruction

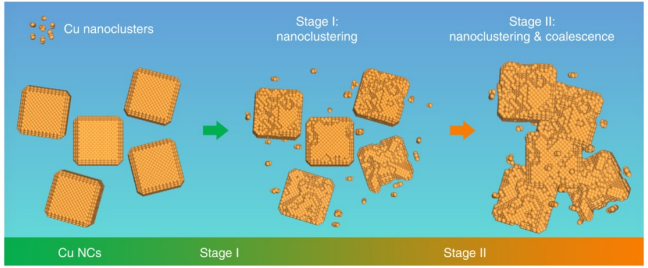
SIRT 30 itterations

Electron microscopy to study degradation process of Cu NPs

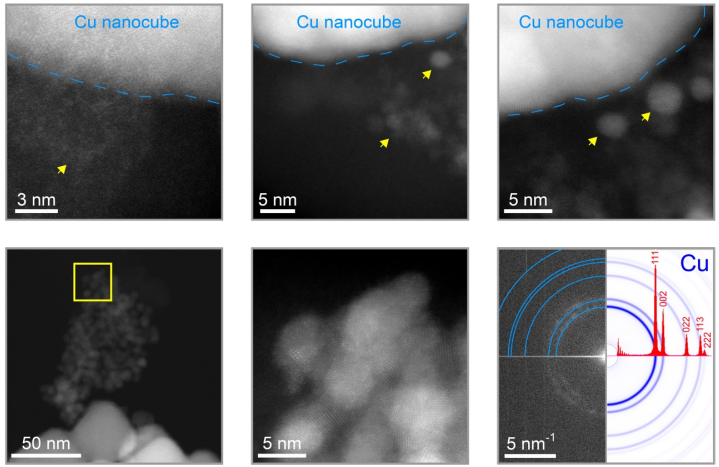
Advanced microscopy techniques and image simulation enabled researchers to uncover potential-driven nanoclustering degradation pathway Cu nanocubes during electrochemical CO_2 reduction.

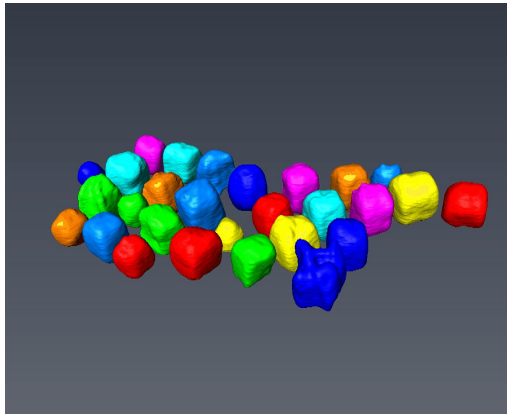


Determination of dominant facets in Cu NC by electron imaging



Followed morphological evolution during operation and correlate it with the electrocatalytic performance





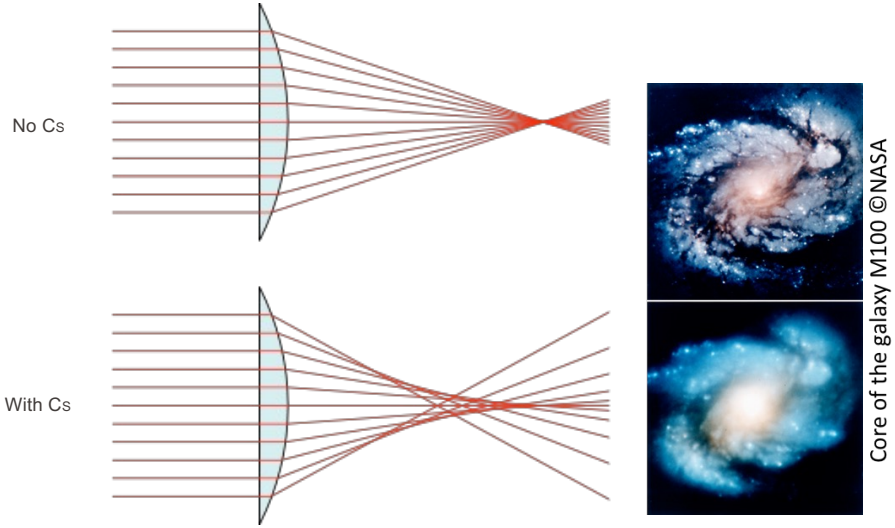
Determination of morphological changes using electron tomography

Huang, Hormann, Oveisi *et al. Nature Communications (2018)*

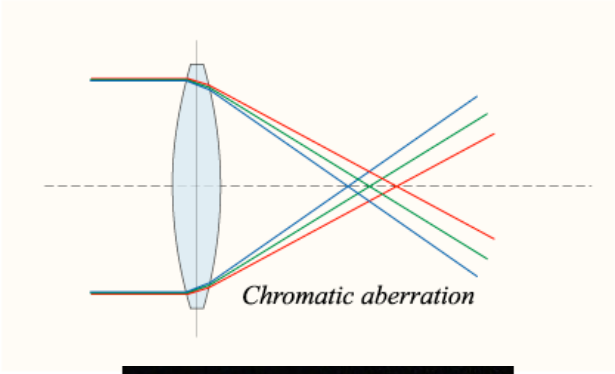
Emad Oveisi

Limitation to spatial resolution: Lens aberrations

Electromagnetic lenses in TEM column are toroidal
Lenses inherently convergent
→ Spherical aberration (C_S) and Chromatic aberration (C_C)



Parallel rays that pass through the central region of the lens focus farther away than the rays that pass through the edges of the lens. Results in multiple focal points and thus a blurred image.



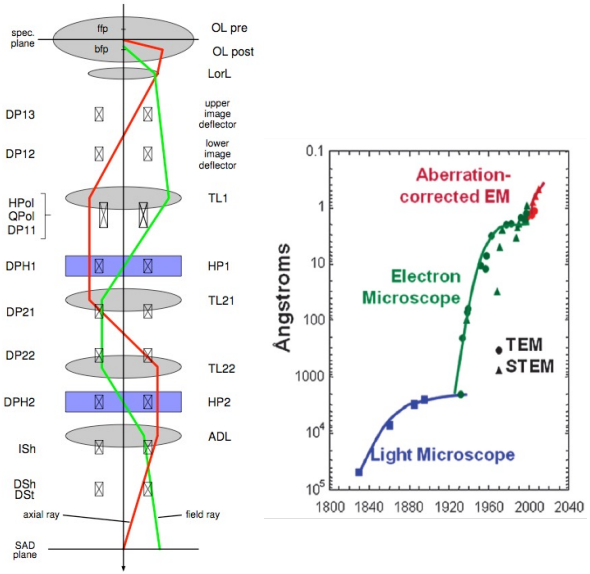
Lens cannot focus all energies (wavelengths) to the same convergence point.

Resolution in TEM limited by aberrations, especially Cs

Cs - aberration correction

Combination of standard radially-symmetric convergent lenses with multipole divergent lenses (e.g. tetrapoles, hexapoles) to tune Cs

Like “glasses” for TEM (or the Hubble)



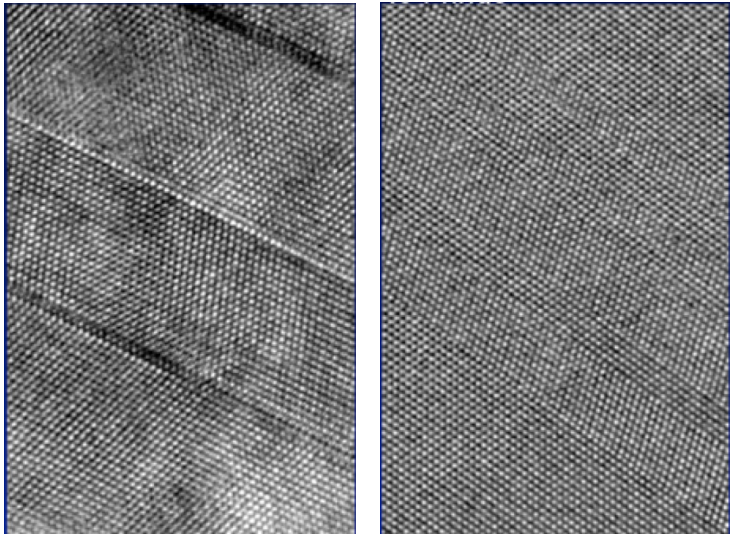
CEOS corrector

→ *Resolution jumps to sub-Å!*

Example: Σ3 grain boundaries in Al

Uncorrected

Cs-corrected



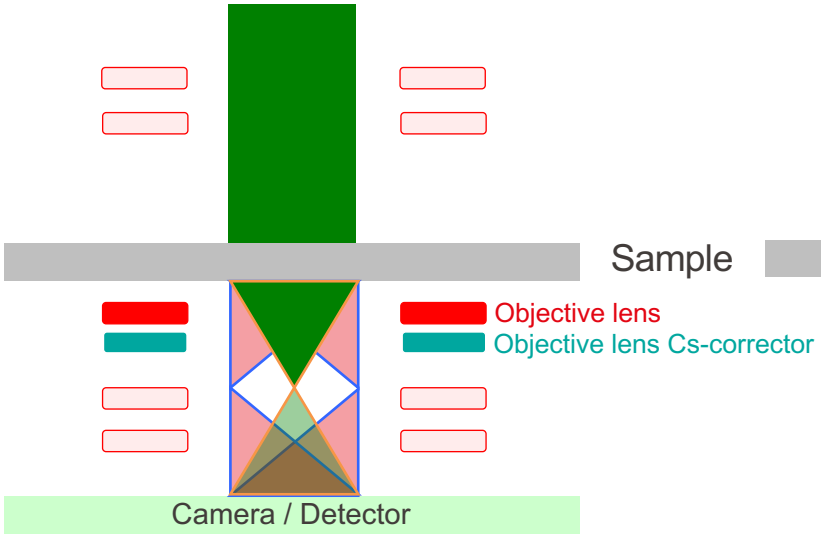
Images: Oikawa, JEOL

Cs - aberration correction

Emad Oveisi

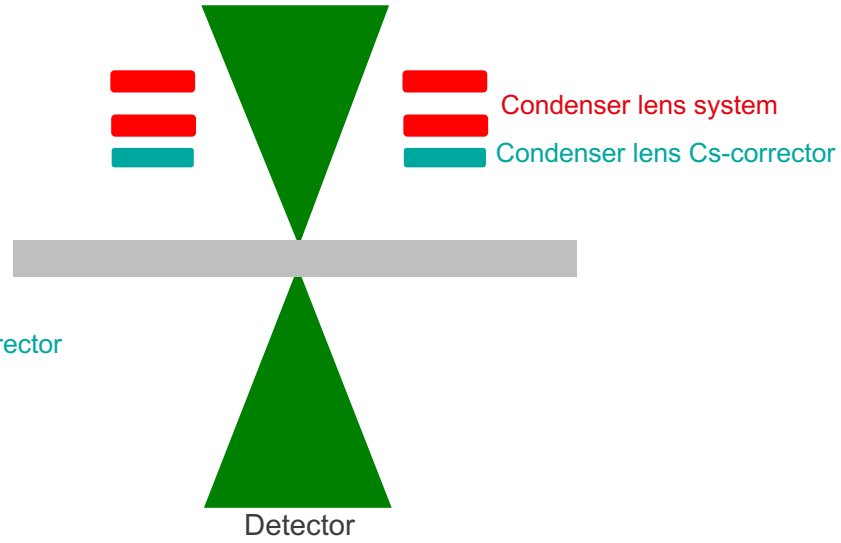
TEM (Image-corrected)

Electron beam (60-300 keV)



STEM (Probe-corrected)

Electron beam (30-300 keV)



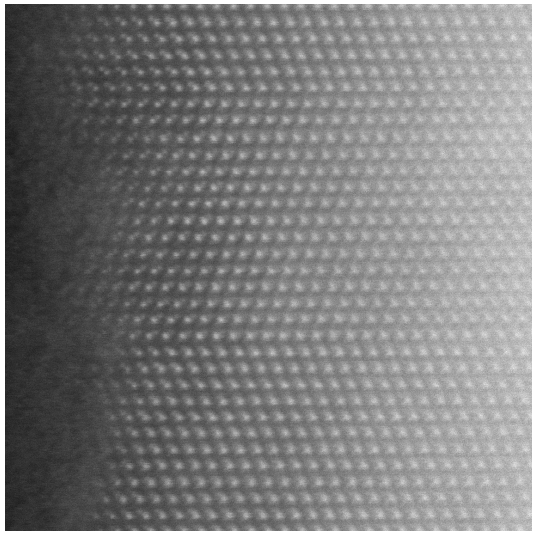
A double Cs-corrected S/TEM has both image and probe correctors

Cs - correction: Probe-corrected HR-STEM

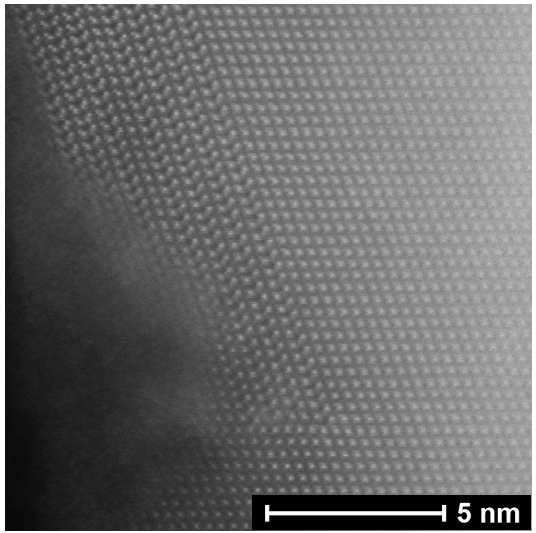
Example: (Al)GaAs nanowires imaged at 300 kV in STEM mode

HR-STEM with sub-Å Cs-corrected probe:

- Simple (quantitative) atomic column contrast
- Reduced sensitivity to small changes in sample orientation
- Image either in focus or out of focus (no contrast reversals with defocus, thickness)



FCC twinning

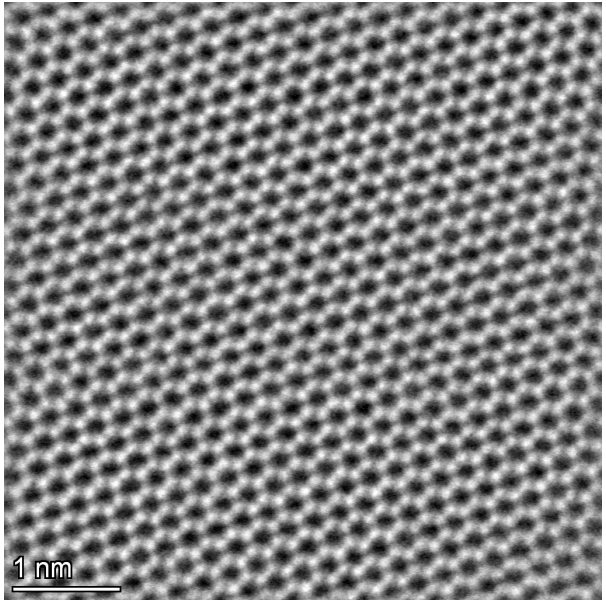


HCP inclusion and dislocation

Images courtesy of D. Alexander, EPFL

Cs-correction: Image-corrected low kV HR-S/TEM

- Cs-correction and monochromatic illumination to reduce Cc allow sub-Å resolution even at lower kV where electron wavelength λ is greater
- Beam sensitive, low contrast materials can be imaged
- Here a monolayer graphene is imaged with 80 keV in STEM mode (IDPC)



- Collaboration with group of Prof. Agrawal, EPFL

S. Huang et al., Nat. Comm. 2018.

Summary

TEM is now not one technique that can be easily summarised, but is split into many specialisms. In essence this is due to the many types of interaction of the electron beam with the atoms of a sample.

Modern TEM instruments are arguably the most versatile analytical tools. Many other possible uses (e.g. imaging of magnetic domains, optical plasmon mapping, in-situ studies) exist..

Aberration-correction and improved instrument stability give sub-Å resolution in TEM and STEM. With lower beam voltages lighter elements can be analysed without beam damage.

Faster, more sensitive spectrometers give unprecedented access to composition, chemistry and physics of materials.

Computer interfaces and software allow acquisition and processing of large datasets.

With the latest instrumentation, the sample and specimen preparation are often the limiting factor!

Some useful literature

Transmission Electron Microscopy by D.B. Williams and C.B. Carter (Springer)

Large Angle Convergent Beam Electron Diffraction by J.-P. Morniroli

Aberration-corrected imaging in transmission electron microscopy: an introduction by R. Erni

Scanning Transmission Electron Microscopy by S.J. Pennycook and P.D. Nellist (eds) (Springer)

Diffraction Physics by J.M. Cowley (North Holland/Elsevier)

Science of Microscopy by C.W. Hawkes and J.C.H. Spence (eds) (Springer)